



Platform of Reliability tOOLs for Failure analysis
dedicated to wide bandgap devices



COS PROOF

jeudi 4 février 2021

*Méthode d'analyse électrique et en bruit BF
pour un diagnostic précis des défauts dans les
technologies III-N*

J.G. TARTARIN – GT2

LES OUTILS DU LAAS, L'EXPERIENCE et LE POSITIONNEMENT NATIONAL/INTERNATIONAL

LES PROJETS DEPUIS 2002 + SUIVI DES ÉVOLUTIONS TECHNOLOGIQUES GaN
(substrats SiC, Si, GaN, Diamant)

QUELQUES CAS D'ÉTUDES

LES PROSPECTIVES ET LES OPPORTUNITÉS VIA PROOF

SYNTHÈSE et DISCUSSIONS

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Electrical noise : from single device to complex system

EUROPEAN KNOW-HOW – labelled by Keysight

Main scientific fields :

> New devices :

- Modelling and noise sources identification - process improvement

> Reliability :

- Reliability through noise measurement, at device and circuit level – process improvement

> Linear & Nonlinear circuits and noise :

- Noise sources modelling under nonlinear conditions
- Low Noise Amplifier design – harshness vs jamming (+ nonlinear noise figure)
- Phase noise modelling (oscillator, amplifier...)

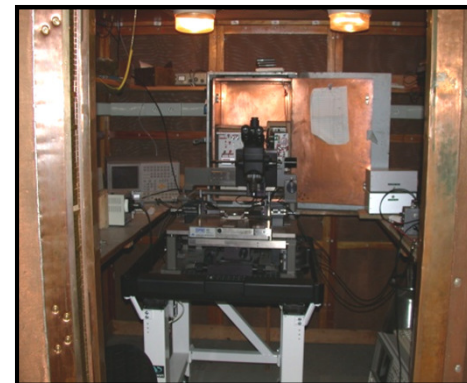
> Noise in complex systems :

- Noise in frequency synthesis,
- Noise in Tx/Rx RF links...

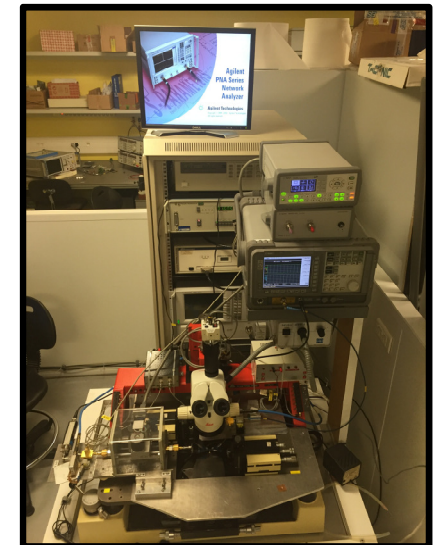
> Noise metrology :

- Low frequency noise ($1/f$ – GR - RTN)
- Microwave linear noise (NF50, 4 parameters)
- Nonlinear HF noise
- Phase noise (RF and microwave sources)
- additive phase noise
- Optical noise (ex : laser RIN, $\Delta\nu$)

Only 1 to 3 active
dedicated researchers!
Need to strengthen the
activity (**PROOF !**)



LF noise measurement



HF noise parameters
measurement 1-40 GHz

Positioned at a European excellence level:

- Cited in European Microwave Journal 2012
- Referenced by Keysight as European Reference Center for LFN in 2016
- Unique experimental setup for LF and HF linear and non linear noise measurement facilities (in Europe at least !)

European Microwaves

*Roberto Sorrentino
and Jan Grahm*

Cooperation with academic laboratories has often specialized in specific topics (for instance, **IEMN** on device processing, simulation, and characterization; **XLIM** on microwave components and systems modelling and simulation; **LAAS on noise**; **IMS** on silicon devices and reliability; **LabSTICC** on filtering; and **IETR** on antenna design and characterization

From IEEE Microwave Magazine,
"European Microwaves", Sept-Oct 2012

*J.G Tartarin,
Professeur Université de Toulouse III*

Noise in France:

How is LAAS is positioned in this area ?

- IEMN Lille (HF noise)
- IMS Bordeaux (LF Noise & reliability)
- IES montpellier (LF noise-Silicon)
- XLIM Limoges (LF Noise and N.L. circuits)

Noise in Europe & Worldwide ?

A small but active community
(almost 500 active researchers
mainly in Europe, USA, Japan)

- *ICNF conference (every 2 years), ESREF, ...*
- *IEEE Trans. Microwave Theory and Technique, Microelectronics Journal, IEEE Elec. Device Letters, IEEE Trans. Elec. Device*



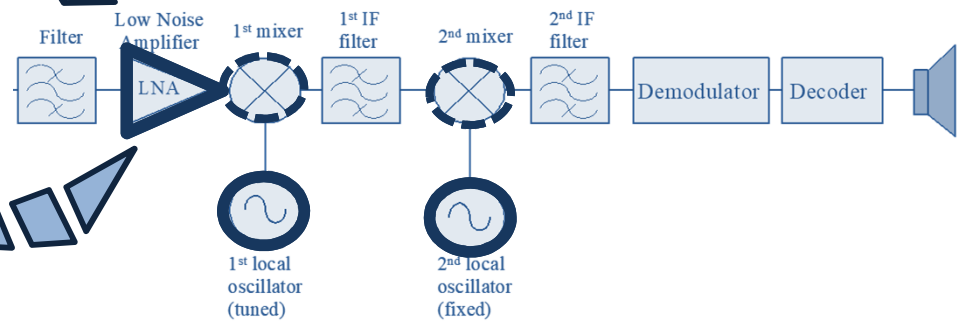
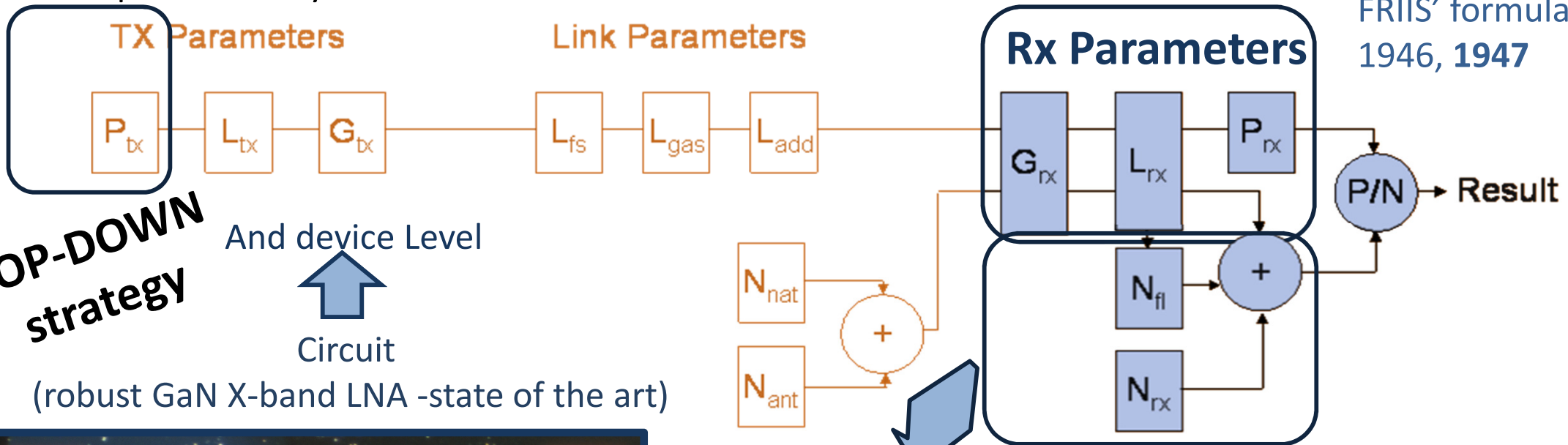
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$$P_{RX} = P_{TX} - L_{TX} + G_{TX} - L_{FS} - L_{gas} - L_{add} + G_{RX} - L_{RX}$$

Power Amp. – reliability

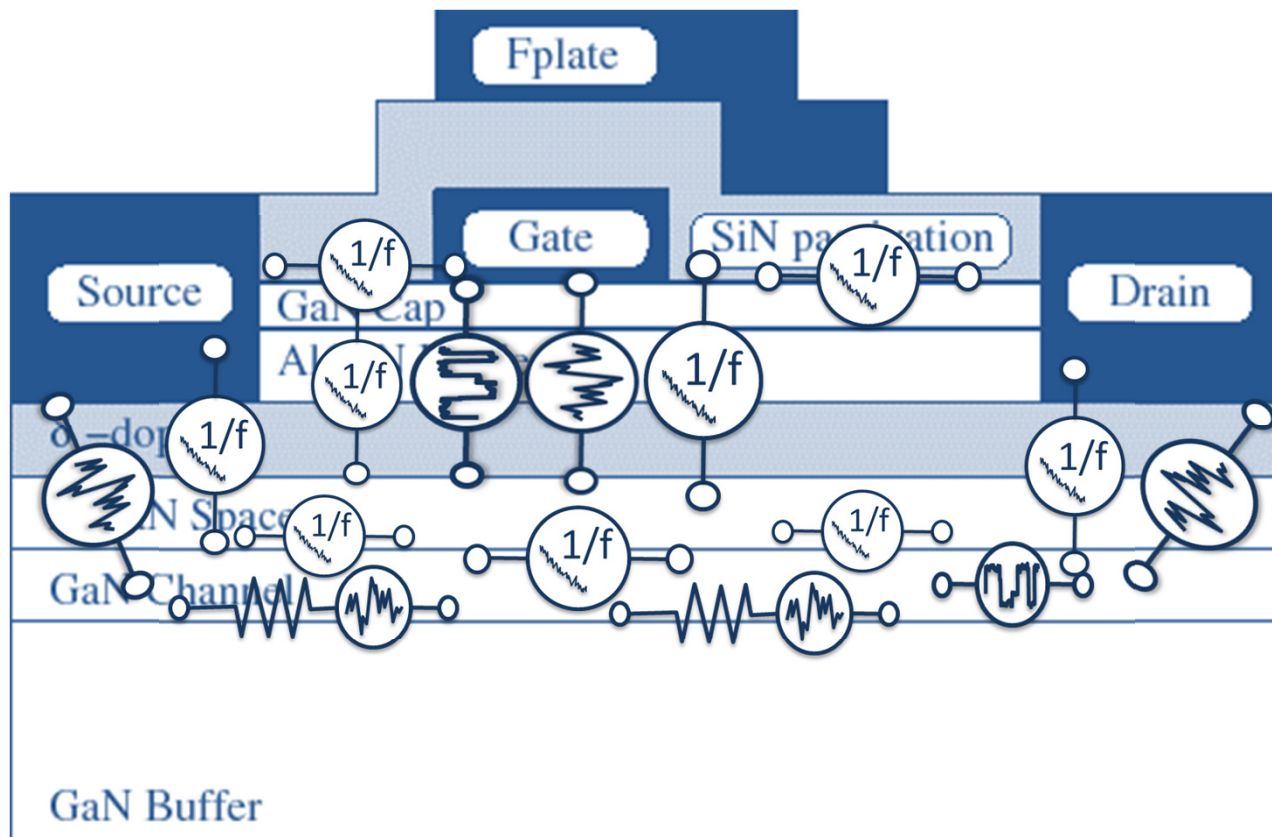


Noise is considered at the receiver's side as it is the place where the signal is at its lowest level

Electrical improvement by frequency & power increase

→ various technologies (III-V, SiGe, GaN, ...)

→ various active devices (HBT, LDMOS, MESFET, HEMT, m/pHEMT, FinFET, nanoFET...)



NOISE REVEALS EVENTS (DEFECTS) THAT :

- SET THE LIMIT OF ELECTRICAL PERF.
- REVEAL WEAKNESSES OF A DEVICE

MEASUREMENTS TOOLS

NON-INVASIVE DETECTION TOOLS OF
MICROSCOPIC DEFECTS



STARTING POINT OF OUR STUDIES !

... and opportunities to play with the
latest technologies !

Electrical improvement by frequency & power increase

→ various technologies (III-V, SiGe, GaN, ...)

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BLIND TEST ON TECHNOLOGY

NOISE REVEALS EVENTS (DEFECTS) THAT :

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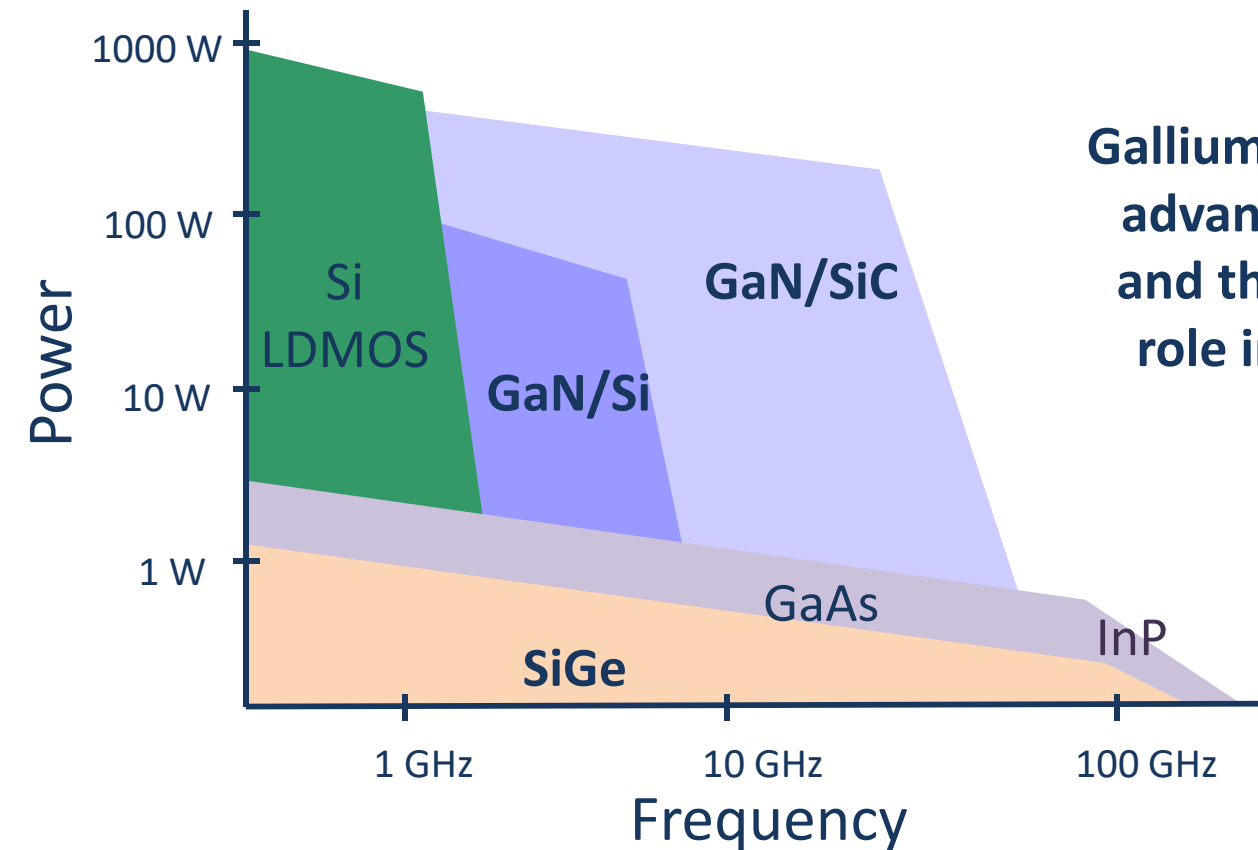
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GaN for HF market



Gallium Nitride and SiGe devices have legitimate advantages in (specific) performances metrics and they will play a more and more important role in defense and radiation-hardened-type devices.

GaAs is in between GaN and SiGe

RF applications will benefit from GaN and SiGe technologies

“In the end, power is voltage times current, and a higher operating voltage makes high power easier. In regard to comparing **GaN versus silicon**, in general, that’s a **complicated answer as they are very different. GaN is still expensive from a wafer cost, but the mask cost is far less than cutting-edge CMOS (28nm CMOS)”**

K. Benson, Analog Devices

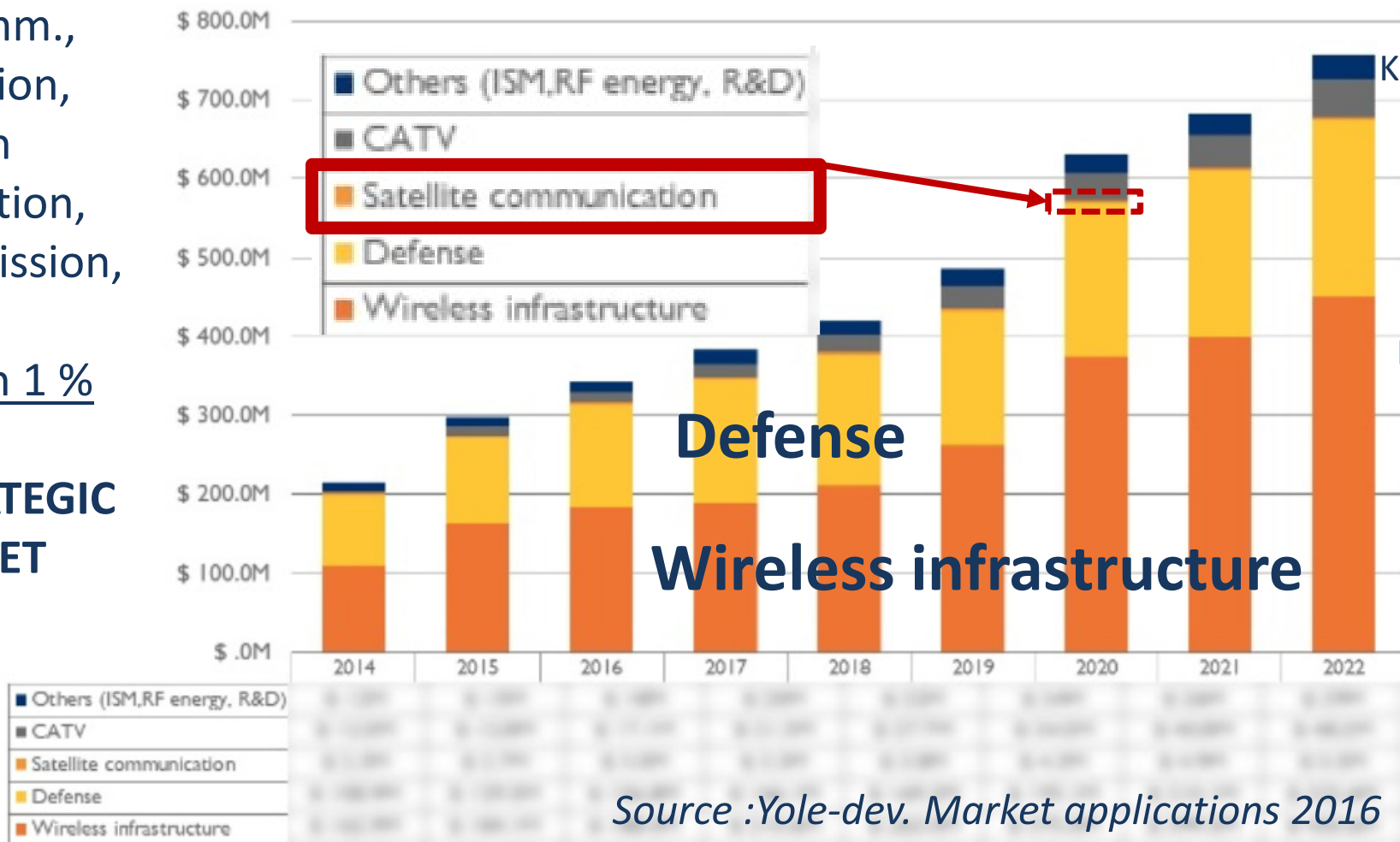
GaN for HF markets – EVOLUTION & TRENDS

Satellite
TeleComm.,
Navigation,
Earth
Observation,
Science Mission,

Less than 1 %

**BUT STRATEGIC
MARKET**

Forecast of GaN RF devices market size



Source :Yole-dev. Market applications 2016

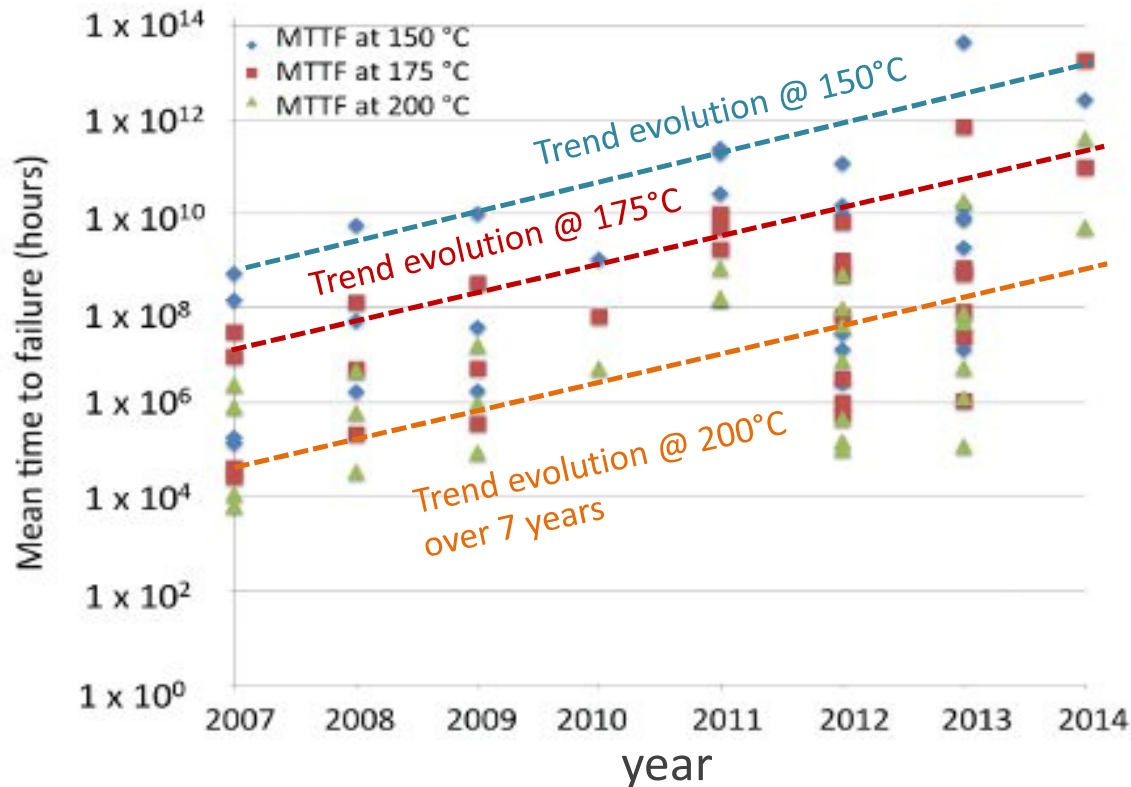
RELIABILITY IS A
KEYPOINT TO PUSH
THE
PERFORMANCES
CLOSE TO THEIR
LIMITS (mainly
THERMAL
MANAGEMENT +
TRAPS)



**NEED
SECURED
FEEDBACK ON
RELIABILITY
OF HEMT**

MTTF: a survey for GaN devices

Reliability, defect analysis → pushing the time-temperature limits



Performances are not necessarily better, but Security Operating Area improves (junction temperature increase for a given MTTF)

Then it is possible to push the x3 x4 power ratio vs GaAs towards the theoretical limit (x8 to x10)

Inspired from a survey of the literature by Glen David Via from the US Air Force Research Laboratory; this figure indicates a steady increase in the mean-time-to-failure of GaN HEMTs.

PROJETS ET COLLABORATIONS INDUSTRIELLES DEPUIS 2002 et 11 thèses GaN sous la (co)direction de JG Tartarin)

Programmes Européens

- ▷ Projet européen TARGET (Top Amplifier Research Groups in a European Team) (2004-2005) :
 -(R) étude sur “Transmitter impact by non-linear and linear effects on Receiver Noise Figure degradation”.
 -(P) mesures du bruit BF et modélisation large-signal des transistors HEMT AlGaN/GaN : “Metric criterion comparisons for LS and noise models assessments”
- ▷ Contrat ESA AO/1-3916/01/NL/CK (P & R de WorkPackages)(2002-2005) : étude des défauts structurels des transistors HEMT AlGaN/GaN développés sur substrats Si, SiC et saphir.

Programmes Nationaux

- ▷ Projet OMMIC (2015-2019 et 2020-2023): développement de structures MMIC GaN bandes X-Ku-Ka (thèses CIFRE et collaboration Afrique du Sud)
- ▷ Projet GaNEX (2017) (P) : robustesse de nouvelles structures HF GaN (avec CHREA et IEMN)
- ▷ Projet GaNEX (2016) (R) : développement d’une plateforme d’évaluation des contraintes RF-Thermiques sur les transistors GaN en bande X et bande Ka
- ▷ Projet ANR GENGHIS KhAN (2011-2014) (P&R) : conception de *Transceivers* GaN MMIC en bande K et bande Ka.
- ▷ Projet ANR REAGAN (2011-2014) (P&R) : étude et modélisation des mécanismes de défaillance des transistors HEMT AlGaN/GaN, filière industrielle UMS.
- ▷ Projet ANR blanc ‘MOREGAN’ (2007-2010) (P) : caractérisation de structures MOSFET GaN de commutation de puissance rapide.
- ▷ Contrat ‘ANDRO’ (RNRT) (2004-2007) (P&R) : identification des défauts corpusculaires intrinsèques des transistors HEMT, (filière GaN sur substrats Si et SiC), élaboration d’un modèle électrique fort-signal et réalisation d’un oscillateur 10 GHz.
- ▷ Action Spécifique ‘Bruit’ (2002-2004) (P) : outils et techniques de mesure et de modélisation du bruit linéaire et non-linéaire/ bruit des dispositifs avancés.

Collaborations directes Universités: Canada (LN2- 2 thèses), et France (IEMN- 2 thèses), Suède (Chalmers), Allemagne (Cottbus)

Collaborations bi-tri-partites : DGA (2 thèses + projets), CNES, RFHIC, OMMIC, UMS, III-V Lab etc.

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SYNTHÈSE et DISCUSSIONS

Reliability studies; example of an academic methodology and tools for non destructive defect analysis

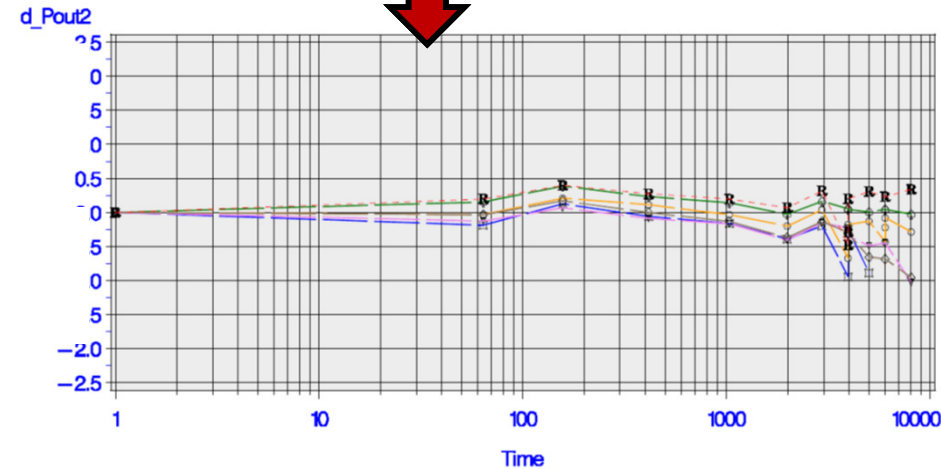
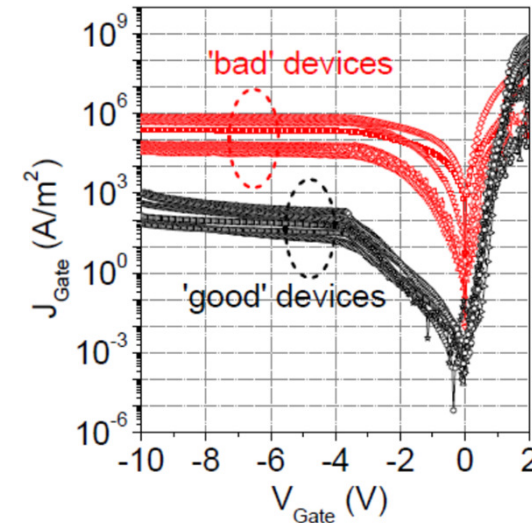
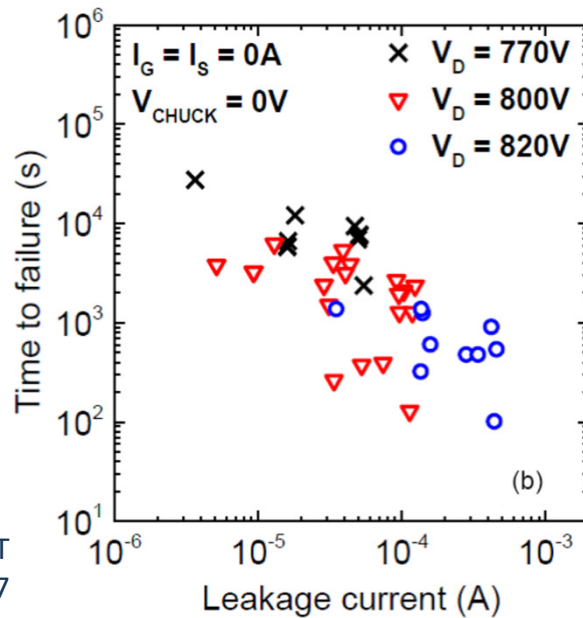
► First (low TRLs) – process improvement
 Iterative and empirical *Find the weakest parts of the device*

QUESTIONS : **WHAT, WHERE, WHEN ?**

COARSE

Industry : process qualification

Find correlations and qualify



Reliability studies; example of an academic methodology and tools for non destructive defect analysis

► First (low TRLs) – process improvement



Iterative and empirical

Deterministic and physical

QUESTIONS : WHAT, WHERE, WHEN ? (WHY and HOW ???)

COARSE

Industry : process qualification

FINE

Research Labs :
Mechanisms & models

What is (almost) known

Thermally activated

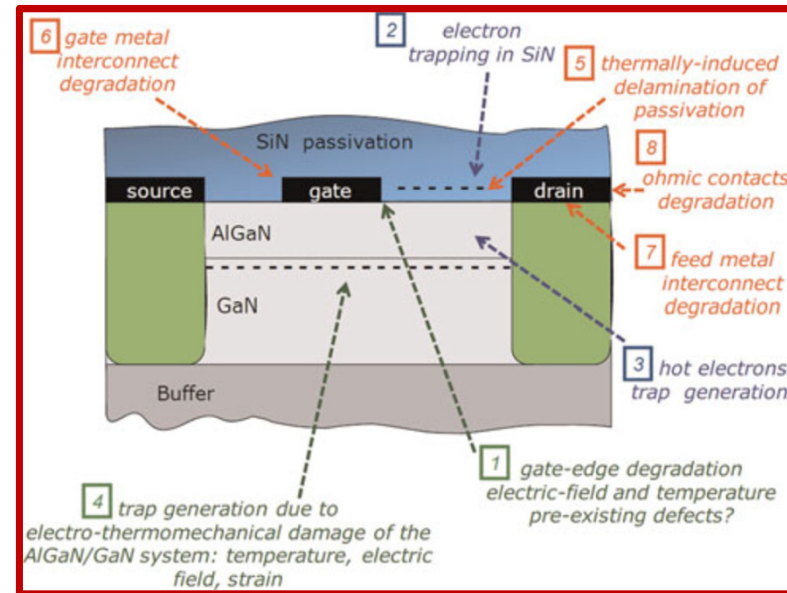
5, 6, 7 & 8

Trapping effects

2 & 3

Piezoelectric effect

1 & 4



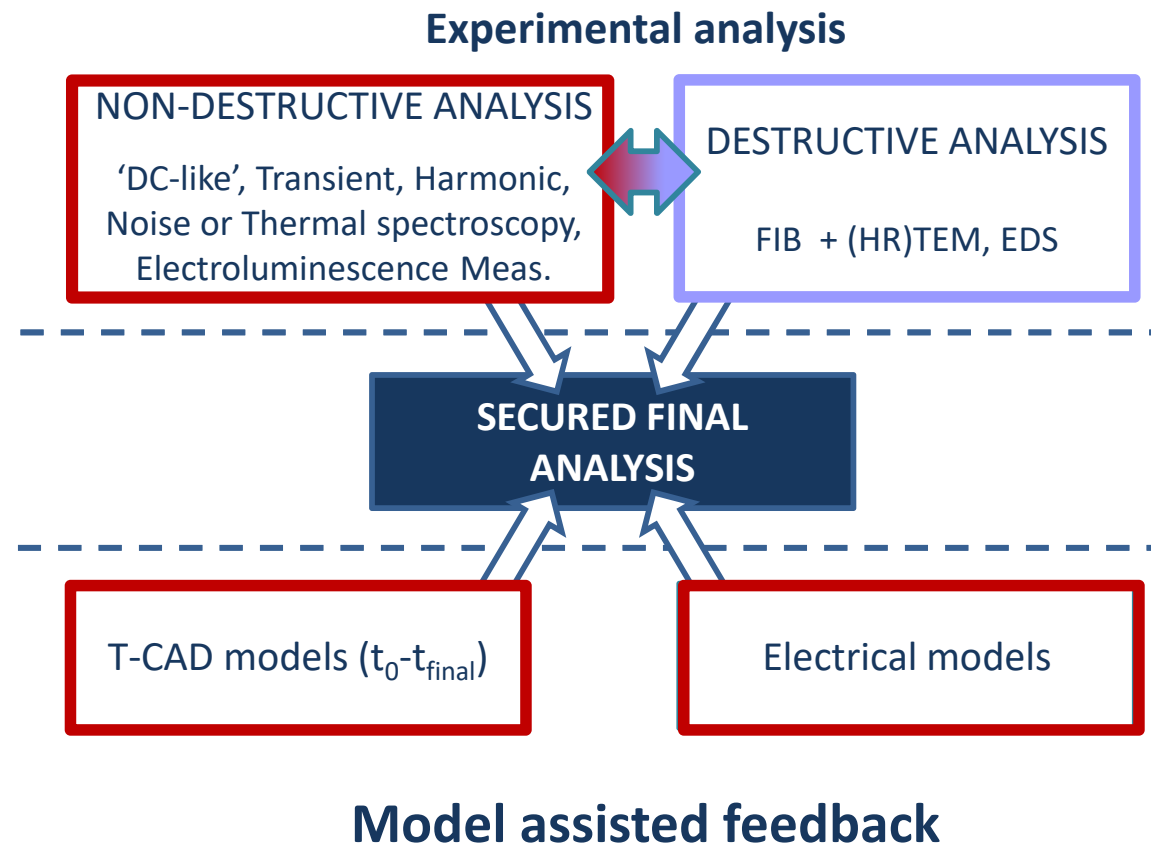
Ref :
Meneghesso
2010 :
reliability issue
GaN HEMT
MWT
cambridge
Press

► Final (high TRL) – process qualification

(process is mastered even if not necessarily understood)

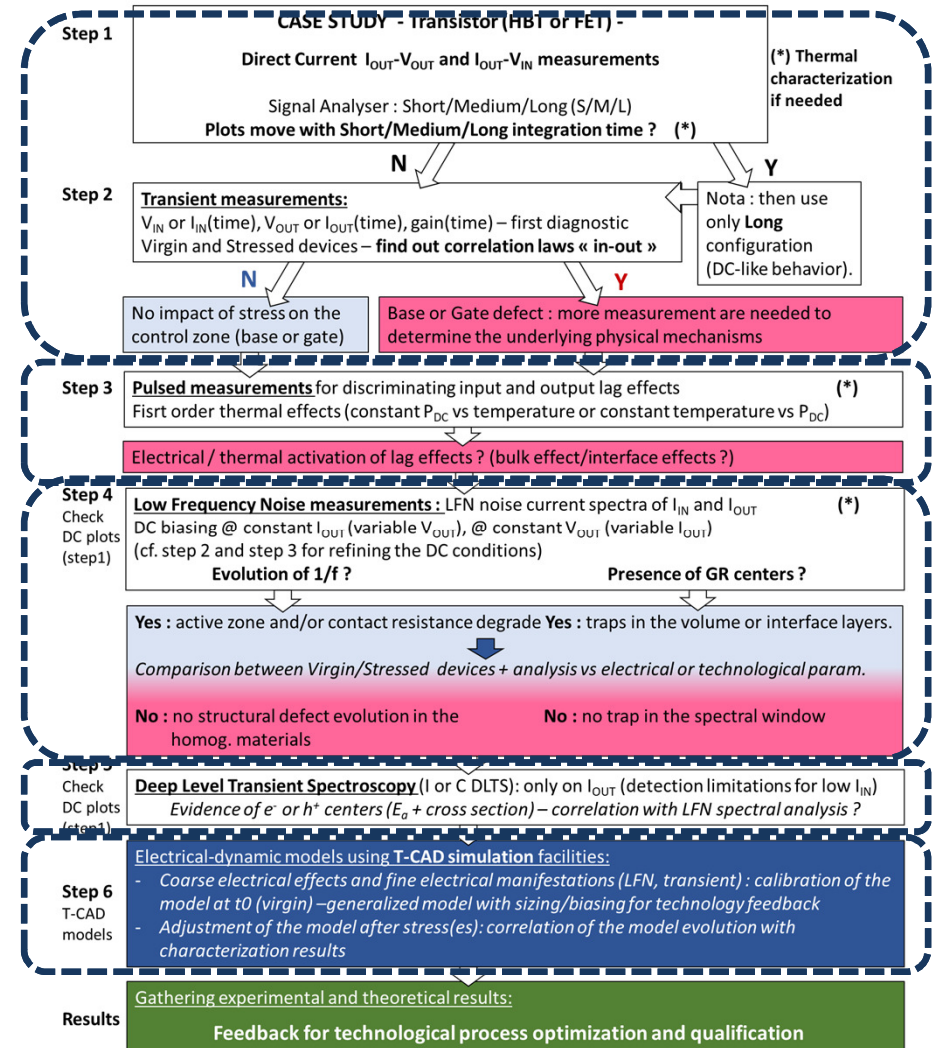
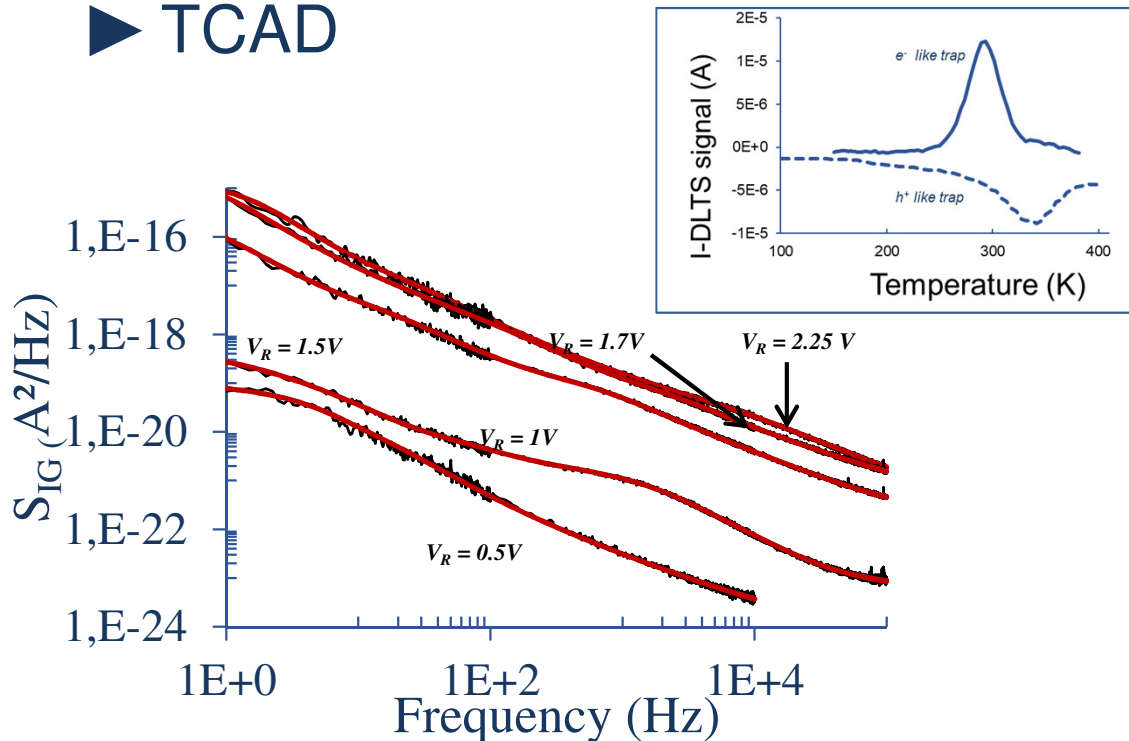
Reliability studies; example of an academic methodology and tools for non destructive defect analysis

- ▶ CASE STUDIES: PROCEDURE FOR RELIABLE DATA ANALYSIS
- ▶ Analyses and Qualification Tools & techniques for low TRL studies



Reliability studies; example of an academic methodology and tools for non destructive defect analysis

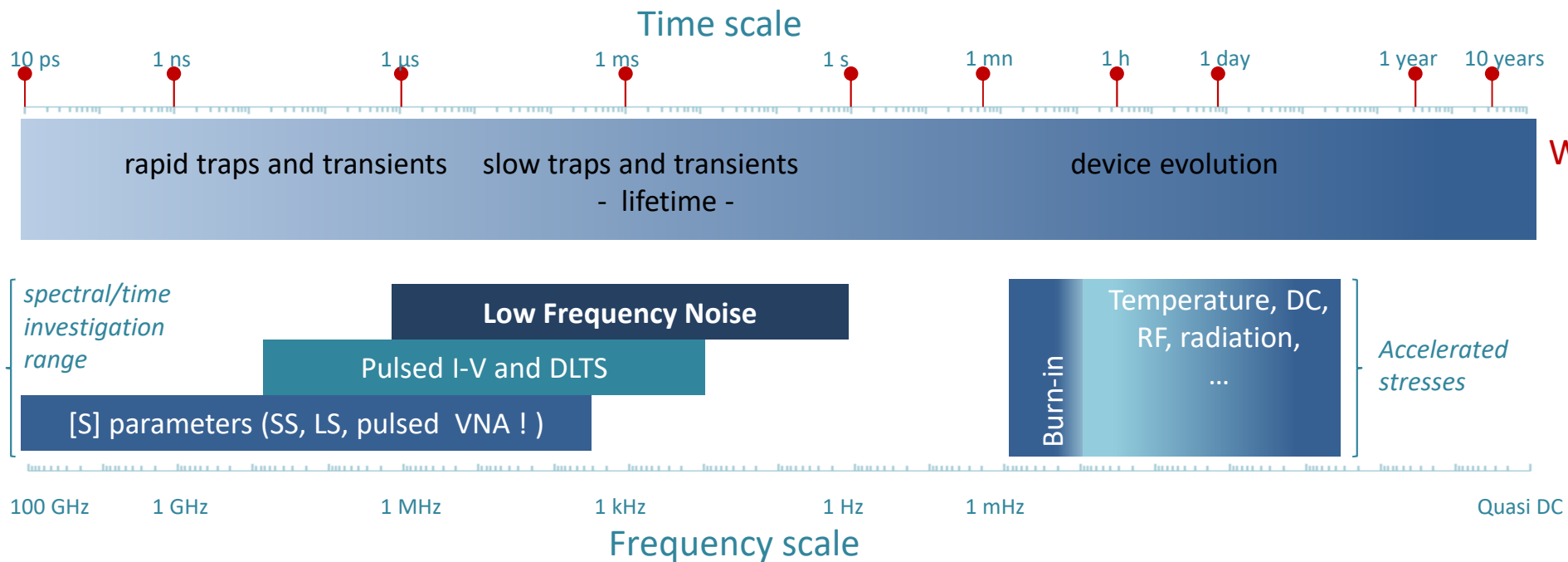
- ▶ CASE STUDIES: PROCEDURE FOR RELIABLE DATA ANALYSIS
- ▶ Analyses and Qualification Tools & techniques for low TRL studies
- ▶ TCAD



Reliability studies; example of an academic methodology and tools for non destructive defect analysis

- ▶ Electrical characterization: mastering the tools and concepts ✓
- ▶ TCAD modeling: based on measured data ✓
but open the ways for the development of next generations of devices
- ▶ LFN measurement (next, few reminders) ✓

Expected behaviors more or less easy to model ✓



What about new (unexpected) mechanisms (new Xperimental setups ?) ✗

Reliability studies; example of an academic methodology and tools for non destructive defect analysis

Generally, **electrical behaviors** feature 'monotonic' electrical laws

BUT defects (or anomalies) can be:

-distributed

-located

in 3D (depends on dimension)

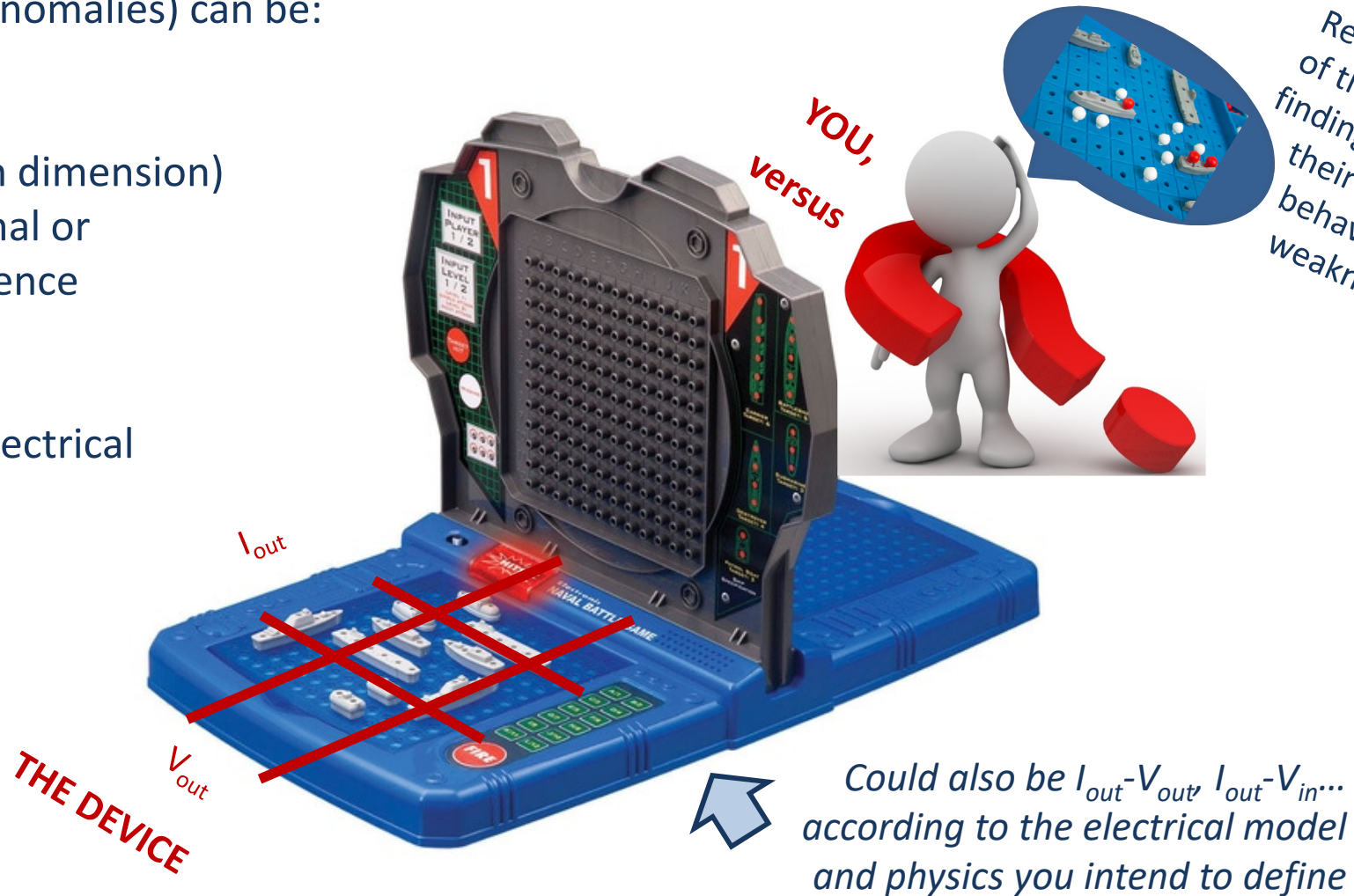
and in their thermal or electrical dependence

(V_{in} , I_{in} , V_{out} , I_{out})

And will impact electrical behaviors

Datasheet / technology maturity

Realistic mapping of the devices, i.e. finding clues about their electrical behavior and weaknesses

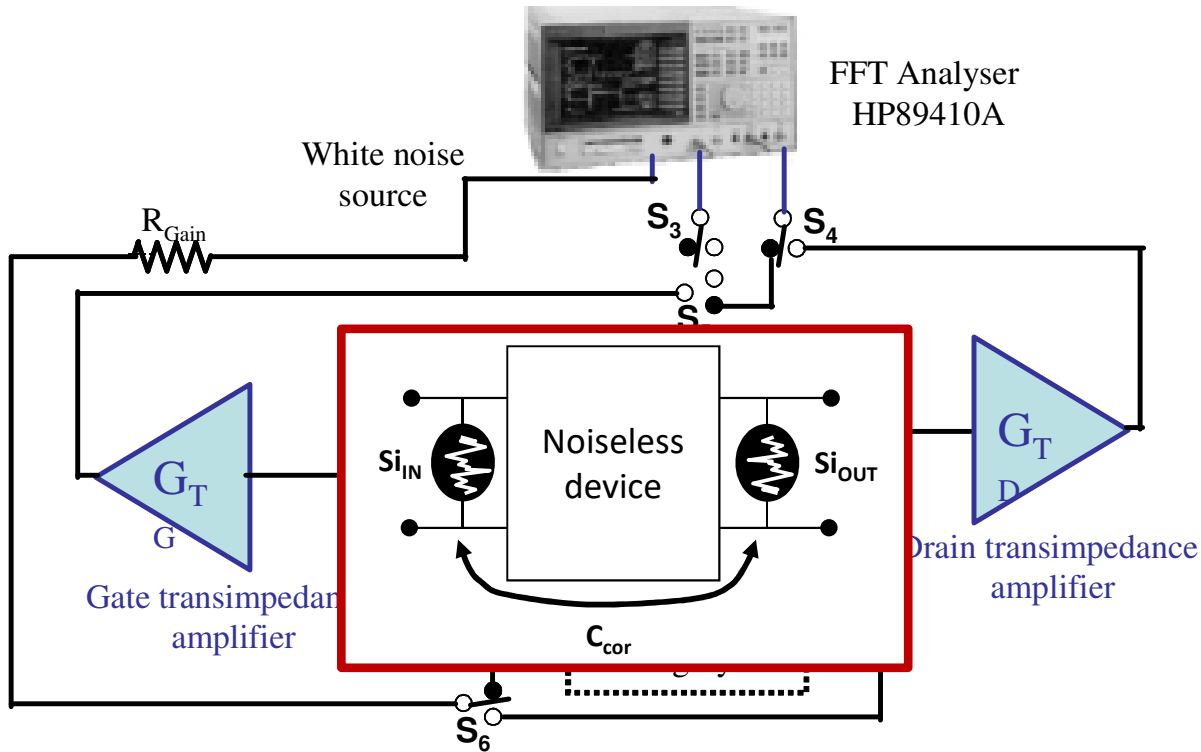


Could also be $I_{out}-V_{out}$, $I_{out}-V_{in}$... according to the electrical model and physics you intend to define

Reliability studies; example of an academic methodology and tools for non destructive defect analysis

► LFN measurement: few reminders

► GaN technologies – studies on AlGaN/GaN and InAlN/GaN technologies from III-V Lab, UMS (GH50 and GH25-10), IEMN lab, RFHIC, OMMIC, (Eudyna)



Faraday shielded room (LF noise)

Non-Linear LF noise (1Hz-1MHz, 2 exp. tools) :

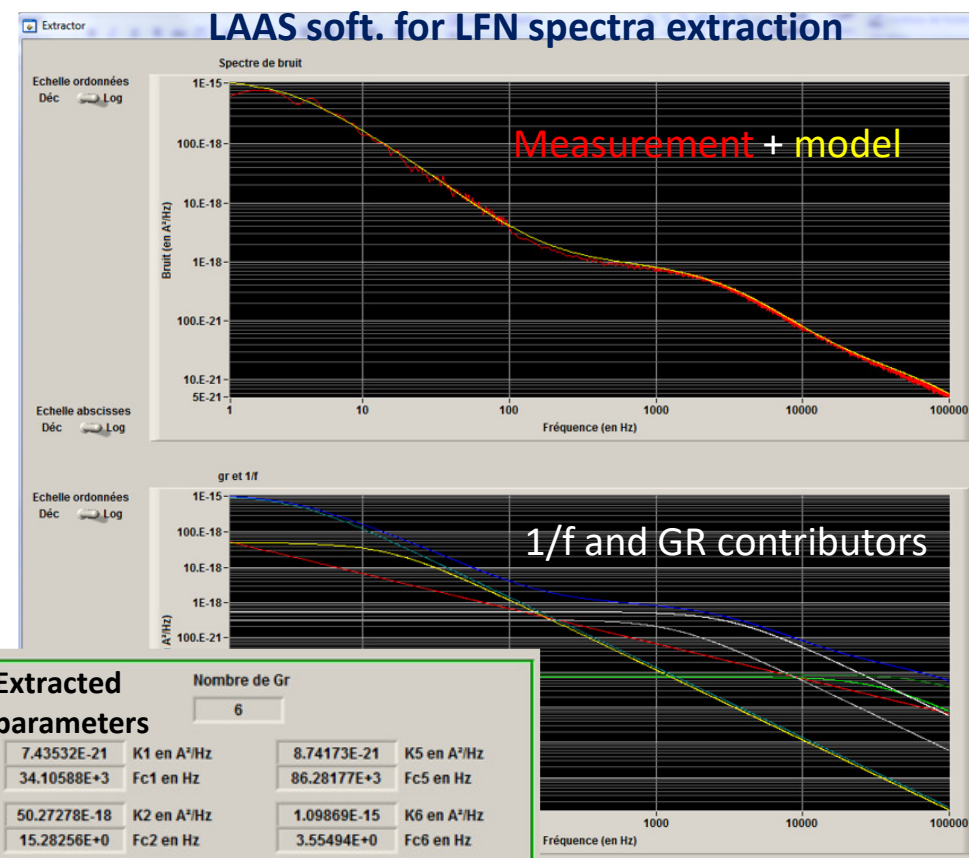
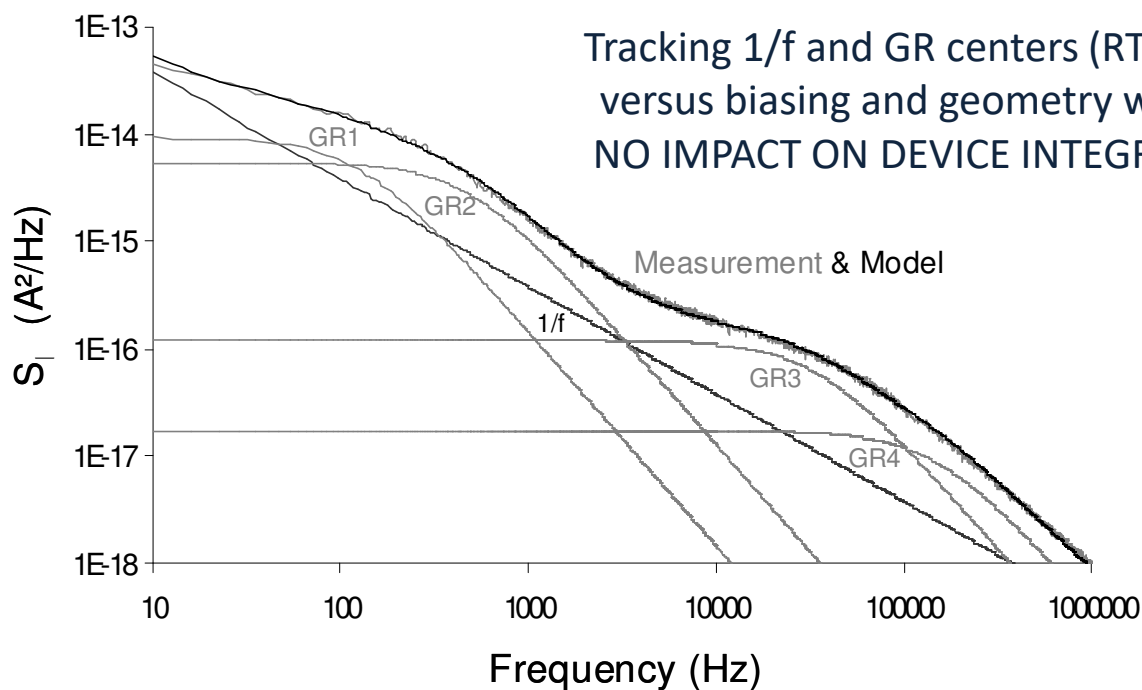
→ $S_{i_{in}} - S_{i_{out}}$ & correlation

Since 2017, LAAS-CNRS has been selected . by Keysight as a European Platform for LFN and RTN characterization

► LFN measurement: few reminders

$$S_{ID}(f) = B \frac{I_D^2}{f^\gamma} + \sum_i K_i^2 \frac{I_D^2 \times \tau_i}{1 + (2\pi f)^2 \tau_i^2} \quad [A^2/Hz]$$

(Ohmic biasing zone)

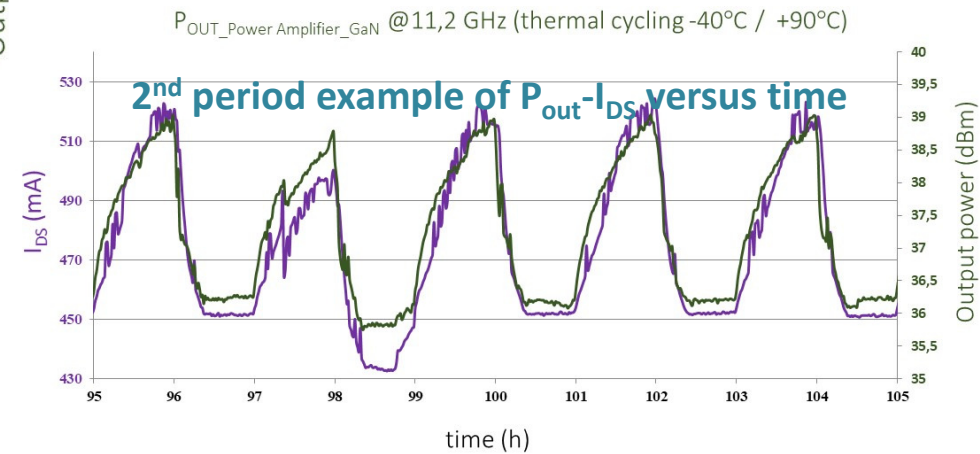
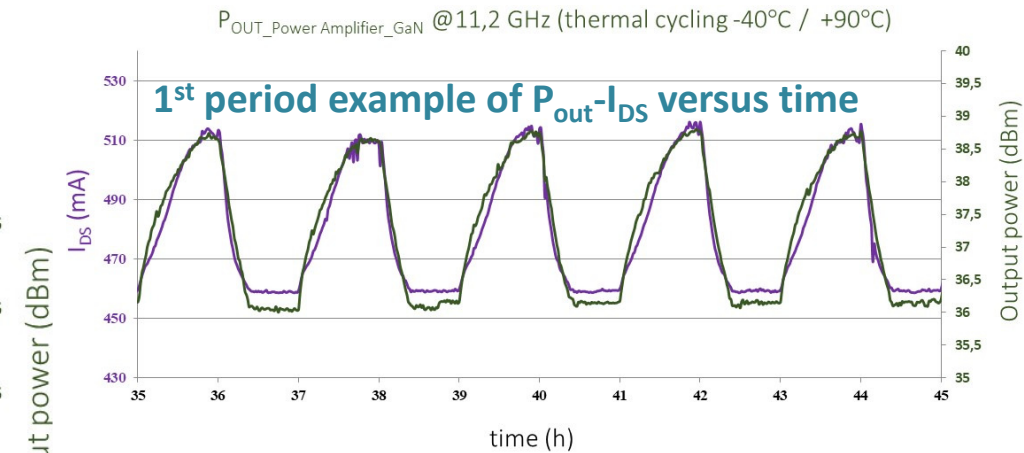
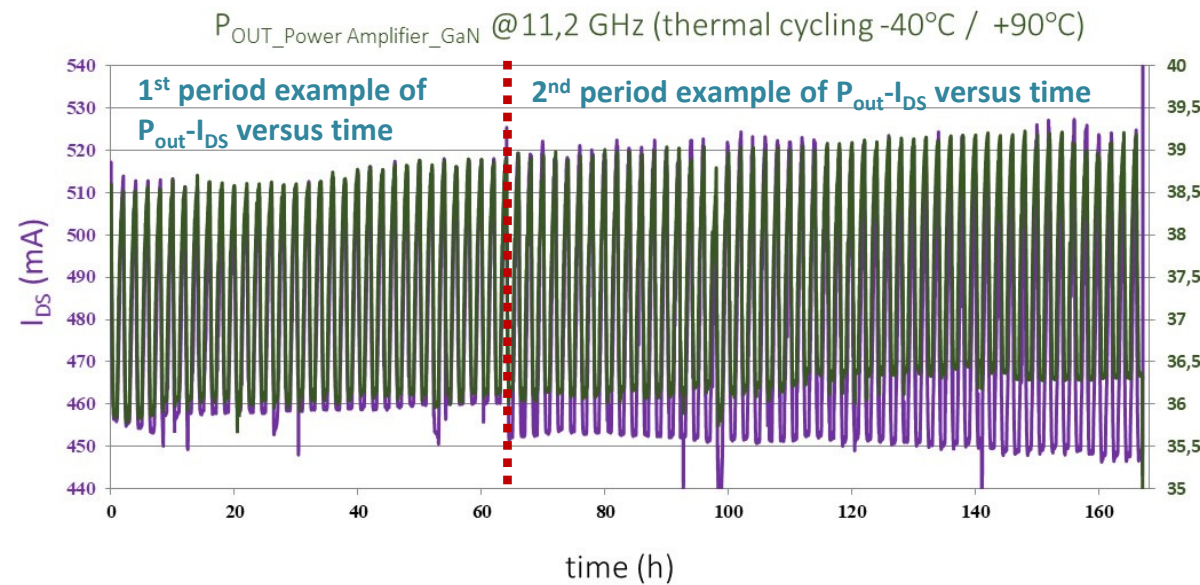


Reliability studies; example of an academic methodology and tools for non destructive defect analysis

► DC-RF-thermal stresses performed at LAAS (TRL 3-5)

Temperature profile: -40°C $+90^{\circ}\text{C}$

Driver correction mode on the calibration path



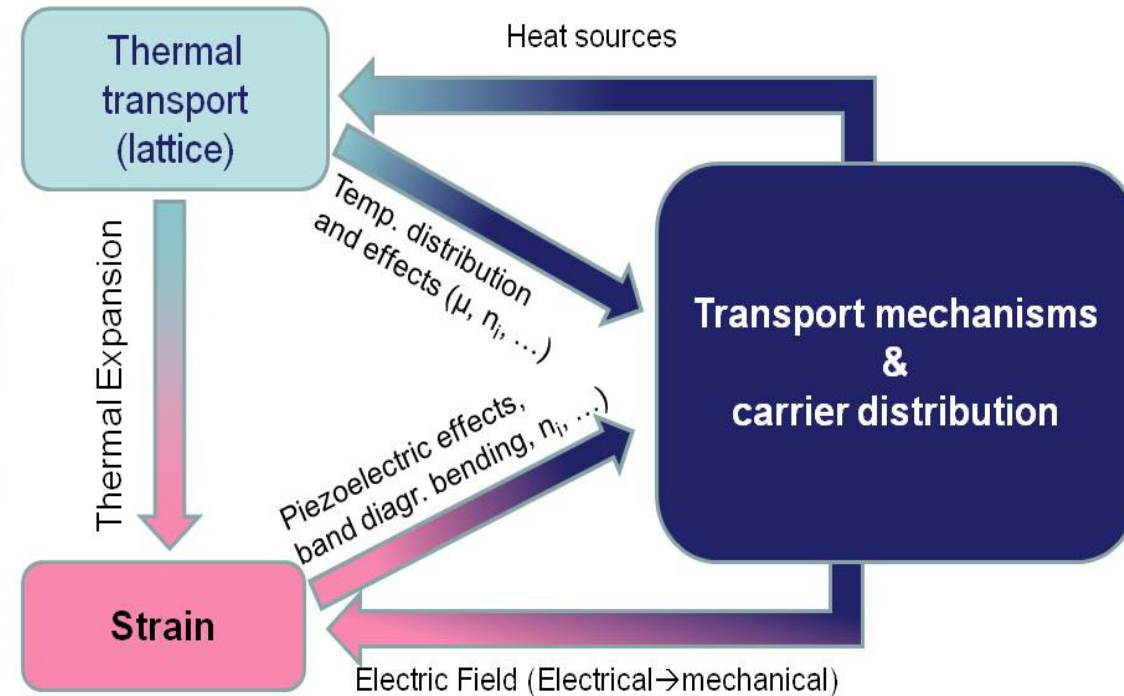
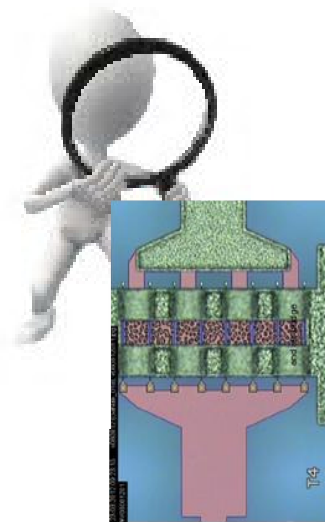
S-parameters measured without removing the device from its environment (X-parameters under development i.e. measurements under same RF stress condition)

Reliability studies; example of an academic methodology and tools for non destructive defect analysis

- ▶ Device Level : strong interactions between electrical, thermal, mechanical effects

The know-how on perf/reliability of GaN technologies will be improved by T-CAD models maturity

based on

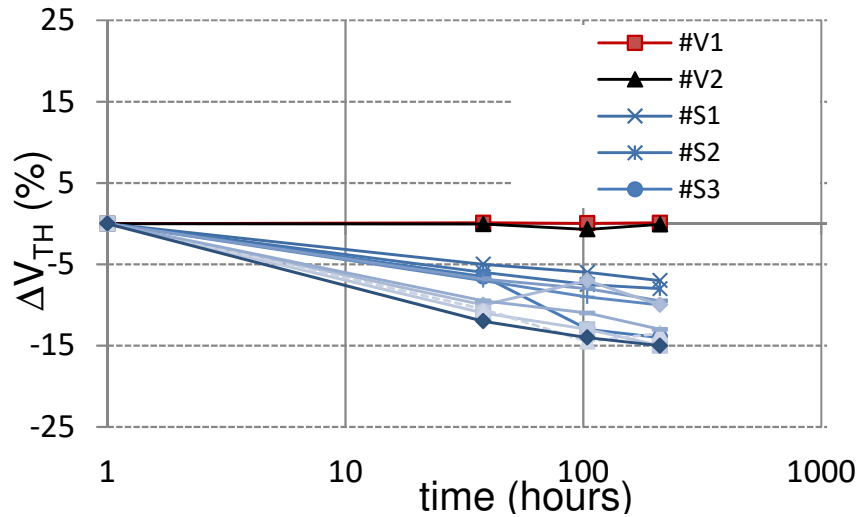


Cross experiments :

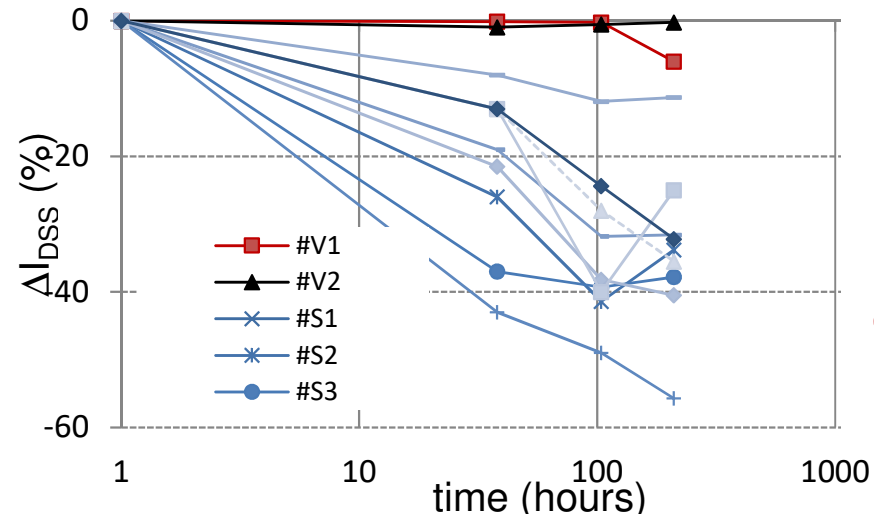
- ▶ **non invasive techniques** (I-V-T static and pulsed, [S] CW / pulsed / large-signal, ?-DLTS, TLS & EL, Low Frequency Noise, nanostructural analysis by Raman spectr., OBIRCh ...)
- ▶ **destructive techniques** (FIB-cut, TEM & EDX, ...) ? *(still uncertainty on the weight of the detected defects; DOES IT PLAY A ROLE IN THE FAILURE PROCESS ?)*

Reliability studies; example of an academic methodology and tools for non destructive defect analysis

► HTOL and HTRB stresses, various batches, samples and techn. declinations

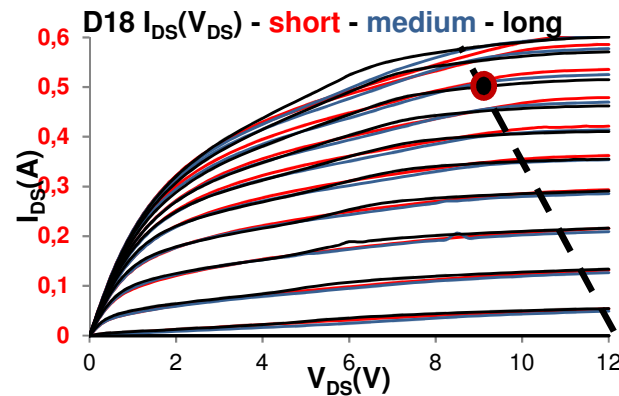
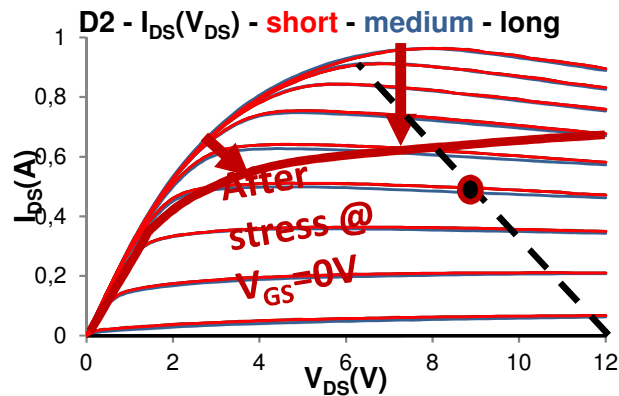


Virgin



Stressed

Possible alteration of the Load Line from DC quiescent point (class A)



From pulsed measurements:
Virgin #TD6 lag < 2%

Stressed (all devices)
-Gate lag : 7%-15%
(-Drain lag < 5%)

Reliability studies; example of an academic methodology and tools for non destructive defect analysis

► CASE STUDY: AlGaIn/GaN GH50 & GH25-10 (UMS)

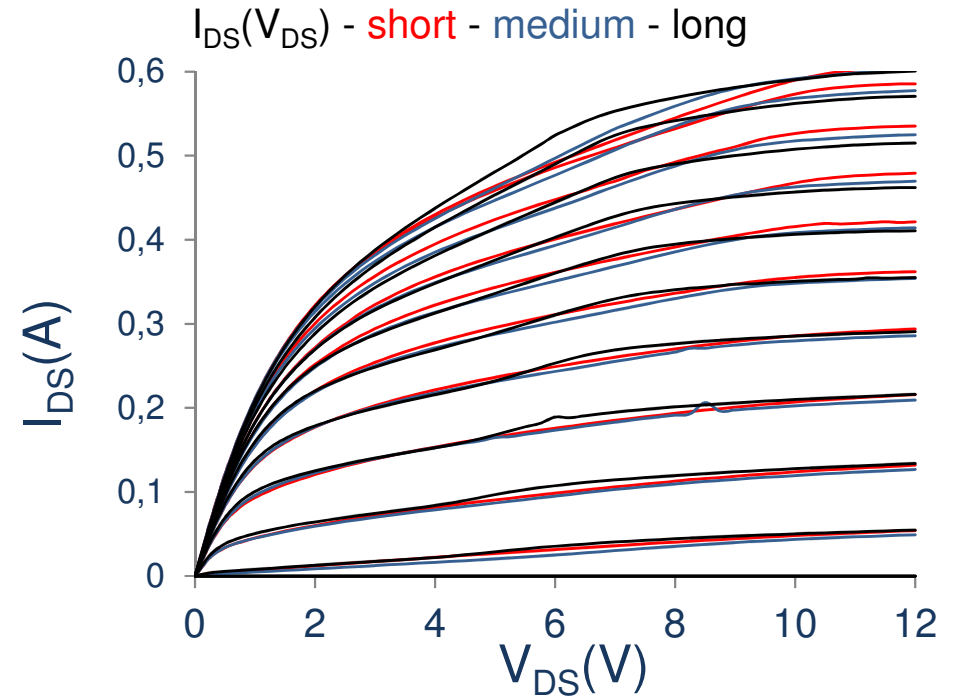
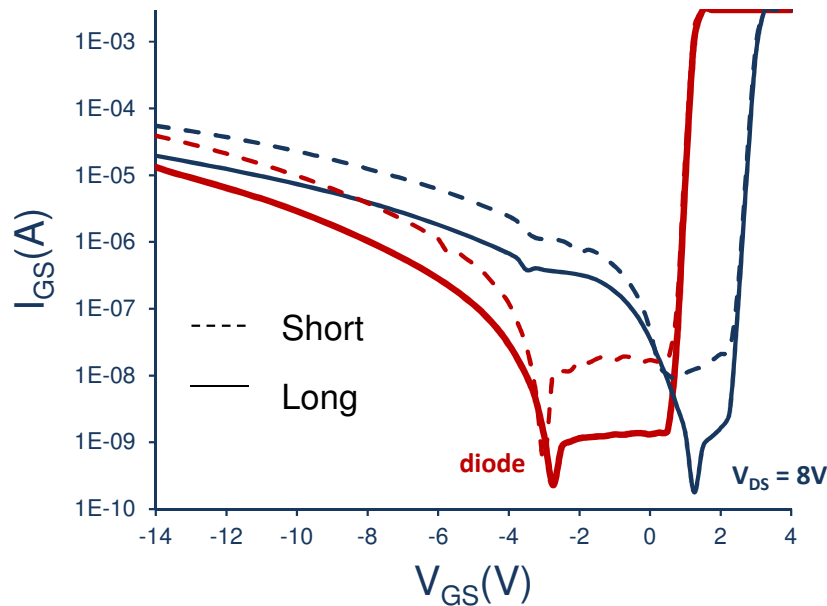
Step 1	Transient DC static I_{GS} and I_{DS} measurements DC static I_{GS} (bias open and shorted) Signal Analyzer (Data Acquisition) (100 MHz) Pulse generator with 500 pF	(*) Thermal characterization if needed for SRH model (100 °C)
Step 2	Transient measurements Plot I_{GS} and I_{DS} versus time Correlation between I_{GS} behavior time?	Note: (then use only Long configuration when back to step 1 measurement get to step 2)
Step 3	Partial measurements for discriminating gate and drain effects Pulsed measurements of I_{GS} constant (in constant), I_{DS} constant (elec. field & constant)	
Step 4	Low Frequency Noise measurements - LF noise current spectra of I_{GS} and I_{DS} DC biasing conditions (I_{GS} constant (in constant), I_{DS} constant (elec. field & constant) Evolution of LF ?	(*) Presence of GR centers ?
Step 5	Deep Level Transient Spectroscopy (DLTS) only on I_{GS}	(*) Evidence of e- or h+ centers and associated Ea

“DC” characterization

Integration Time

short: 640 μ s
medium: 20 ms
long: 320 ms

I_{GS} (diode) and I_{GS} transistor

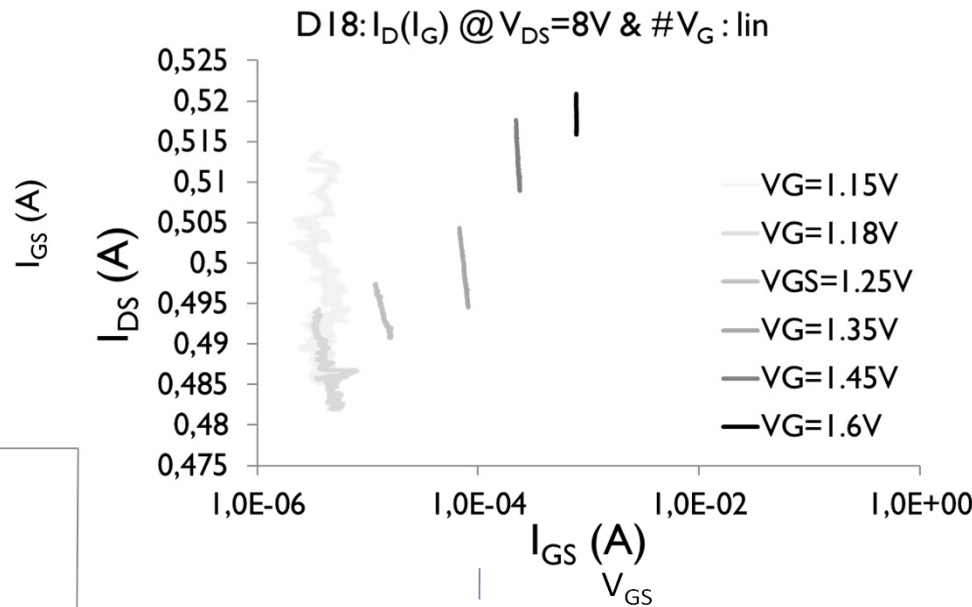
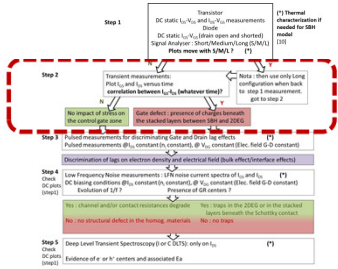


Interaction of charges with specific zones of the transistor !

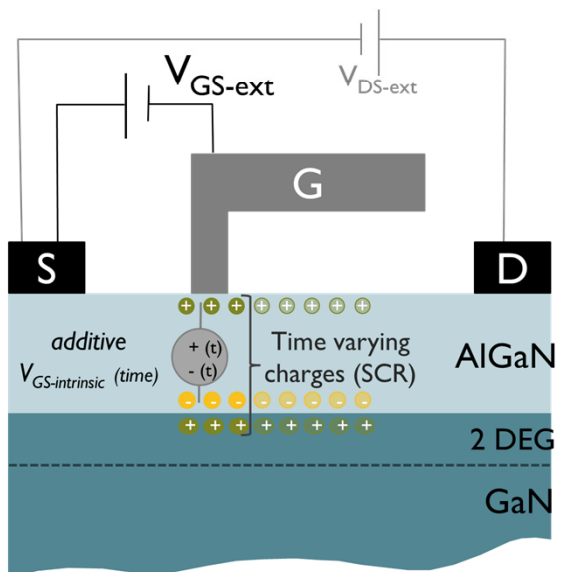
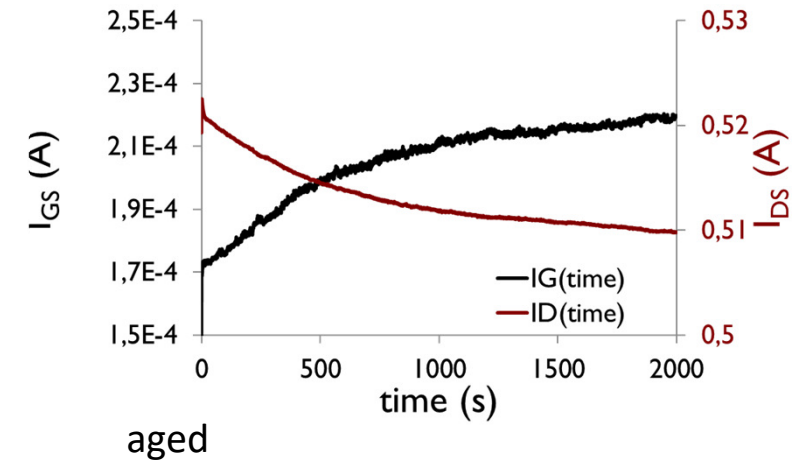
→ Consequences on S.O.A for space or large volume markets

► CASE STUDY: AlGaN/GaN GH50 & GH25-10 (UMS)

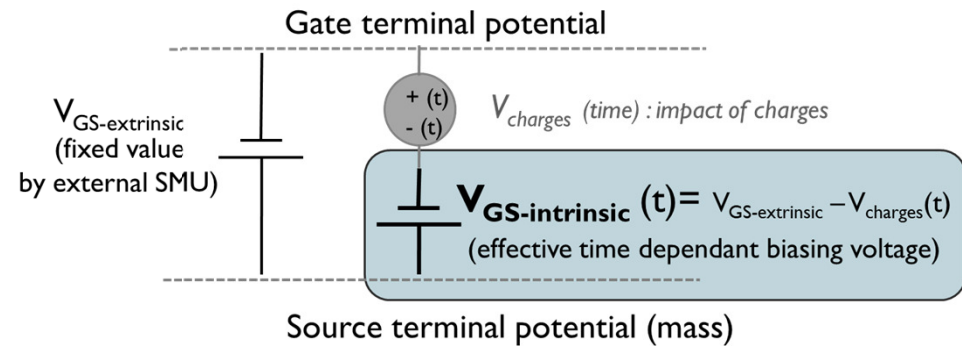
Time domain characterization



D18: I_G - I_D (time) with $V_G=1.45V$ & $V_{DS}=8V$



Correlation between I_{DS} and I_{GS} versus time (ONLY FOR STRESSED DEVICES)
 → same induced cause: real time variations of DC quiescent V_{GS} .

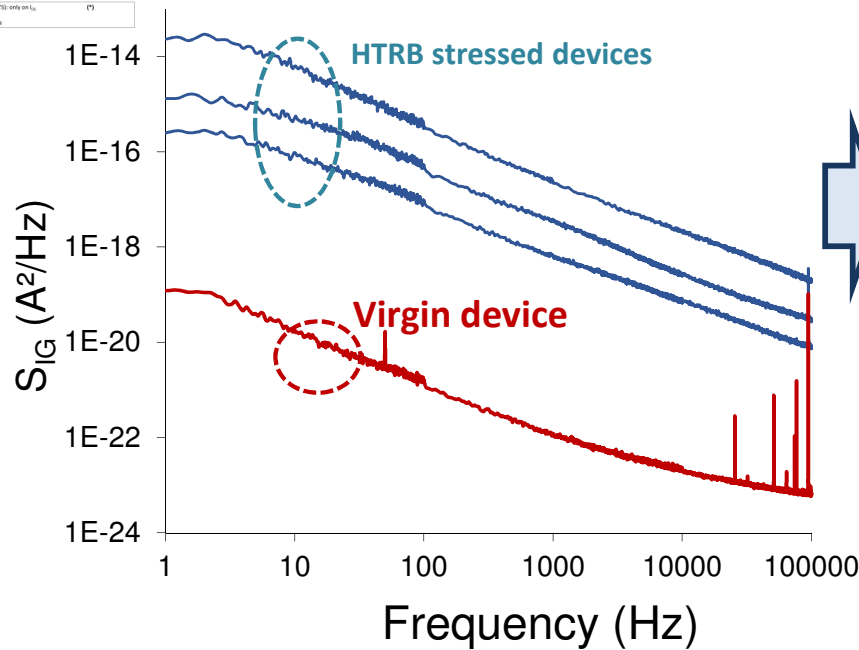
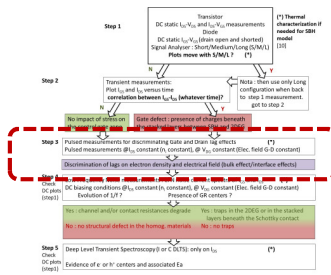


Ref : Lazar et al. in Microelectronics Reliability Journal – Elsevier- 2015

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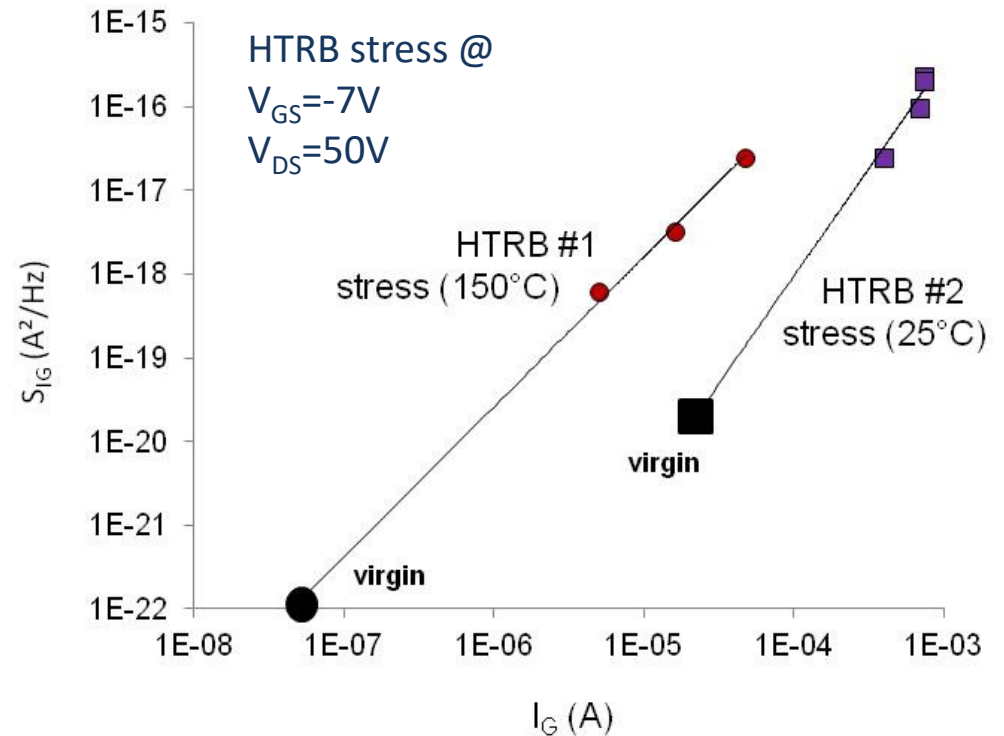
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Noise spectroscopy



-diode alone
-transistor mode

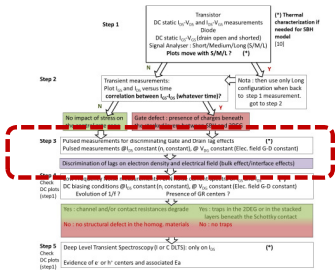
Ref : Tartarin et al. IEEE ICNF 2017



Leakage current as marker of failure events ! S_{IG} also gives a finest signature of carrier's path/interactions in the control zone and lateral/vertical leakage zones

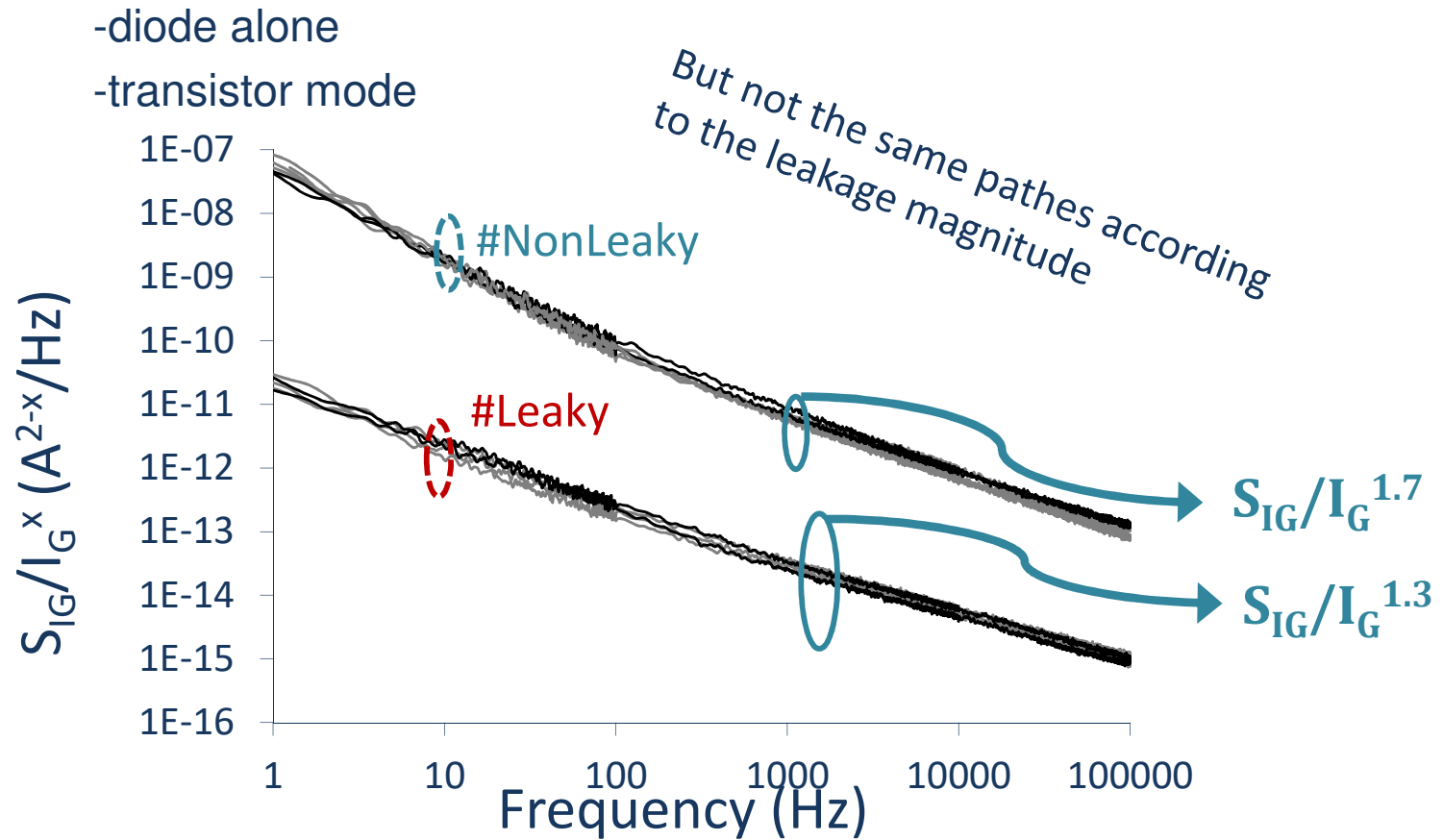
► CASE STUDY: AlGaN/GaN GH50 & GH25-10 (UMS)

Noise spectroscopy



► LFN
 (#Leaky and #NonLeaky)
 dim. 0,5x4x400µm²

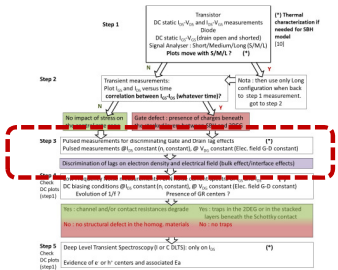
-diode alone
 -transistor (saturated) mode



i.e. same leakage mechanisms, same defects in **Transistor** and **Diode** biasing mode

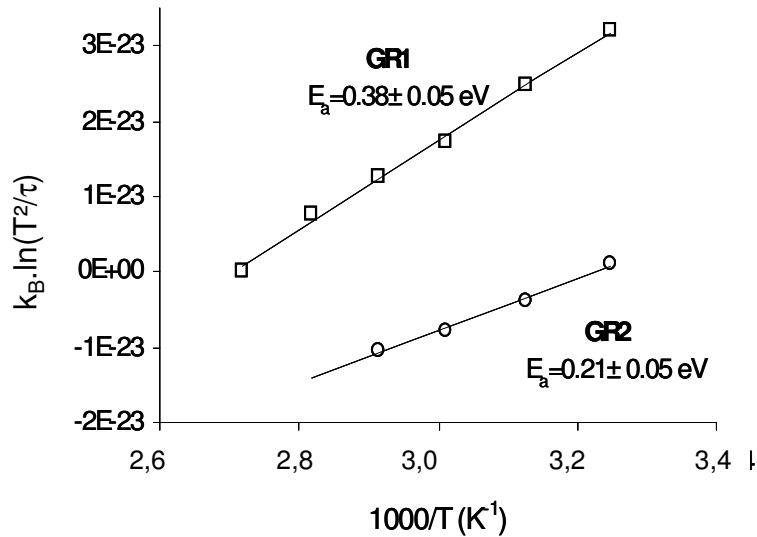
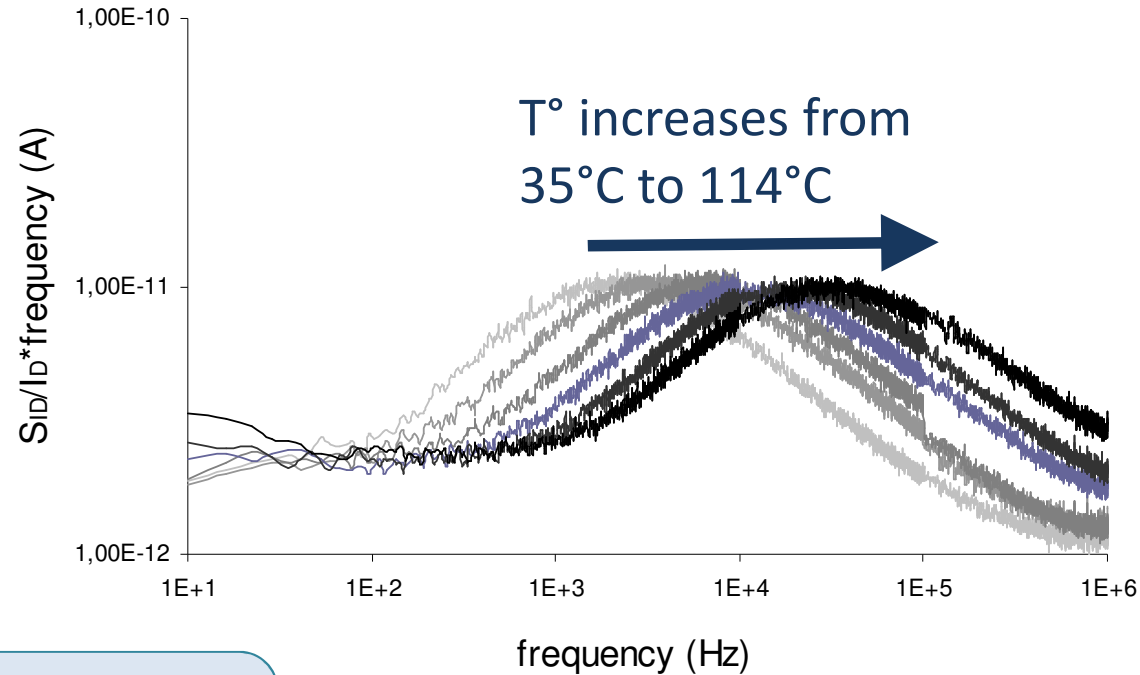
► CASE STUDY: AlGaIn/GaN GH50 & GH25-10 (UMS)

Noise spectroscopy



GR centers evolution vs temperature (saturated zone)

- The magnitude of $S_{ID} \times \text{frequency}$ is constant
- Extraction of GR_1 and GR_2 from each GR 'bulge' (T°)
- Extraction of E_A from Arrhenius plots



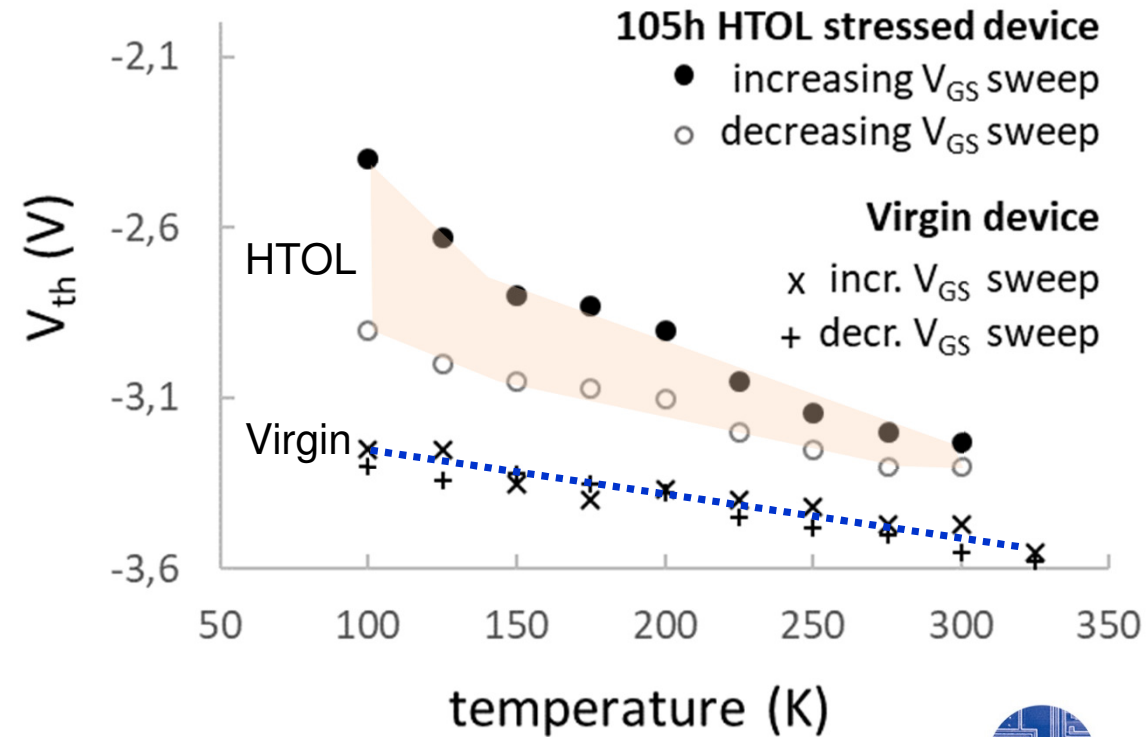
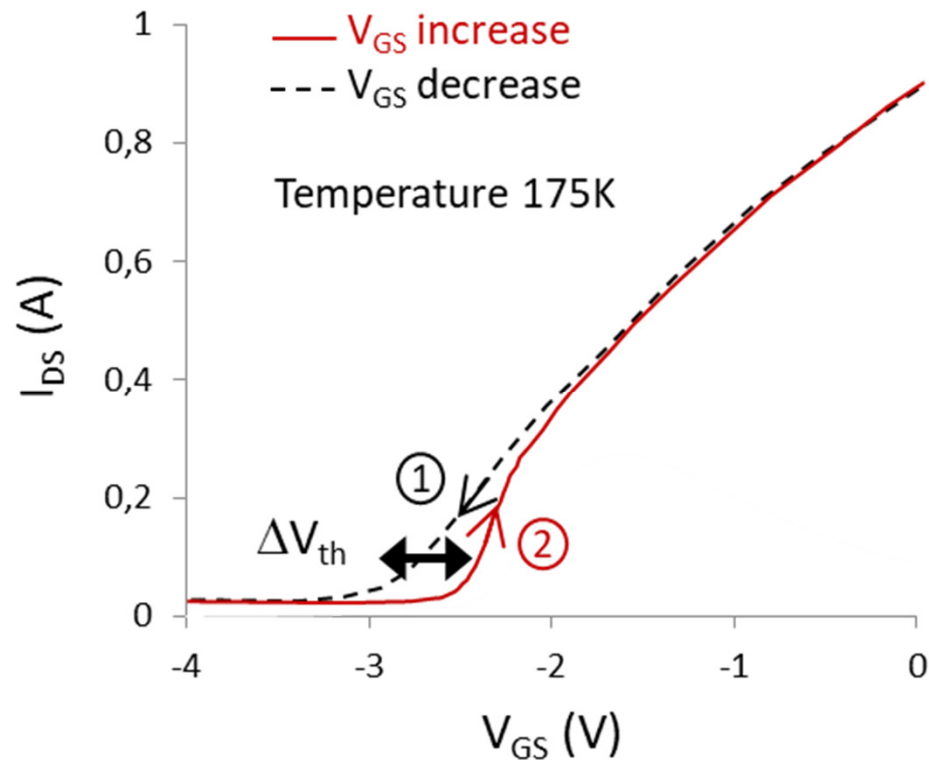
$E_{A1} = 0.38 \pm 0.05 \text{ eV}$
 $E_{A2} = 0.21 \pm 0.05 \text{ eV}$

Ref : Soubercaze IEEE MTTs 2006

Thermal charac: V_{th} drift

(incr. decr. V_{GS} sweeps)

- V_{th} also depends on the sweeping conditions for V_{GS}
- Sweeping conditions (increasing/decreasing V_{GS})

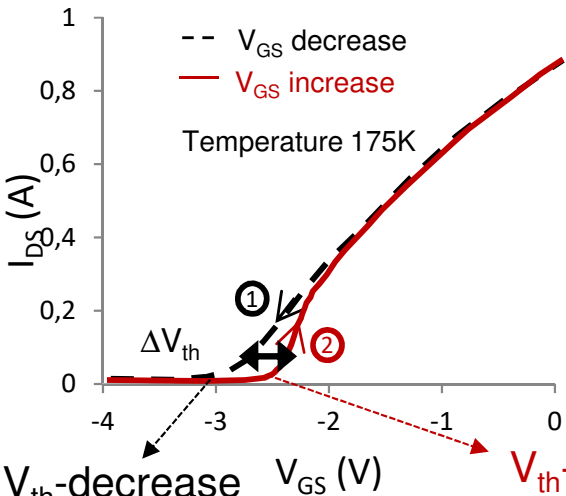


Thermal charac: V_{th} drift

(incr. decr. V_{GS} sweeps)

- V_{th} drift depends on V_{GS} / or \ sweeping condition

$\Delta V_{th} = 0,1V @ 200 K$
 $\Delta V_{th} = 0,5 @ 100 K$



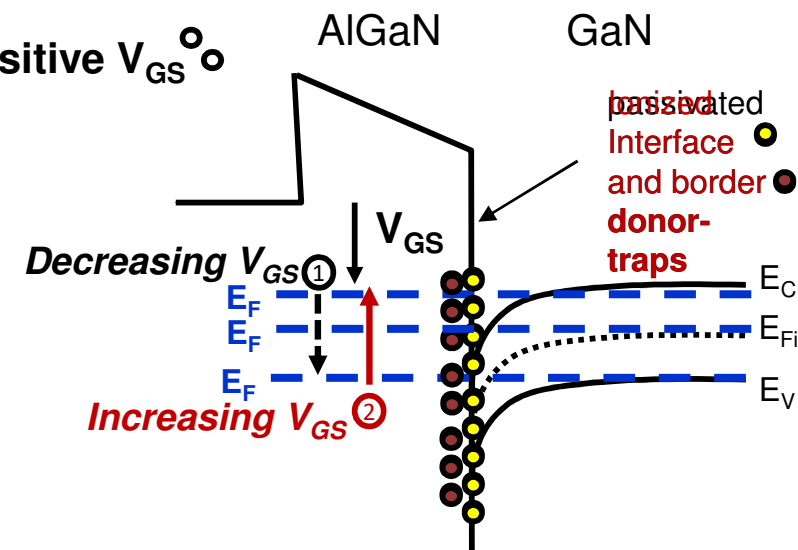
① donor-traps are passivated at positive V_{GS}

Decreasing V_{GS} from +3V to -6V:

Donor remain passivated till the 2DEG is fully depleted

$\rightarrow V_{th-decr.}$ is not modified during V_{GS} sweep (so $n_{i-decr.}$ in the 2DEG)

@ reversed V_{GS} donors are ionized



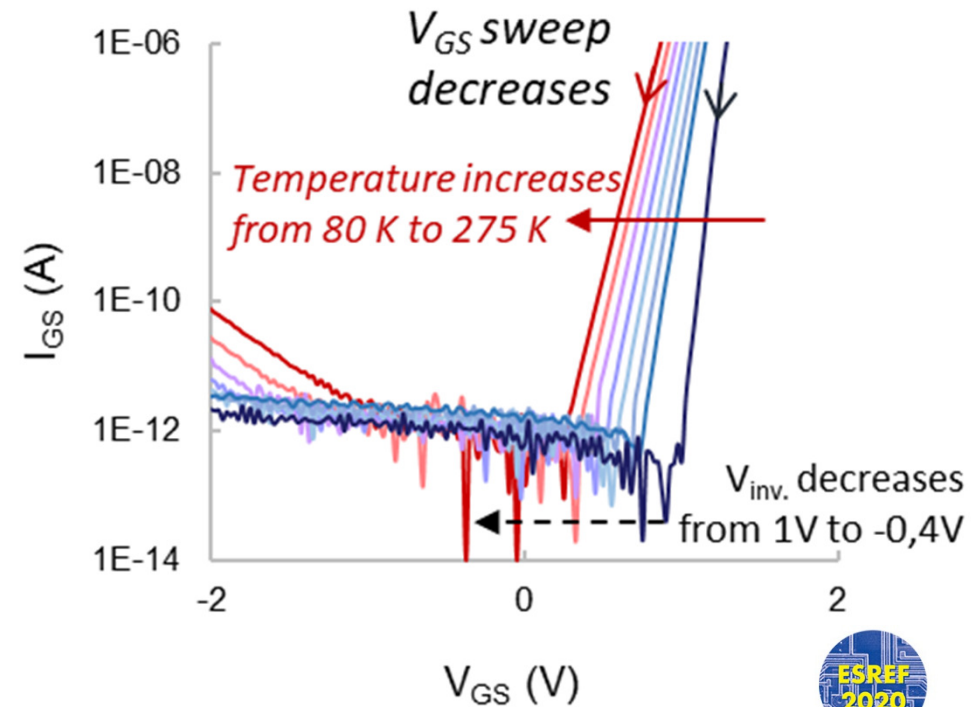
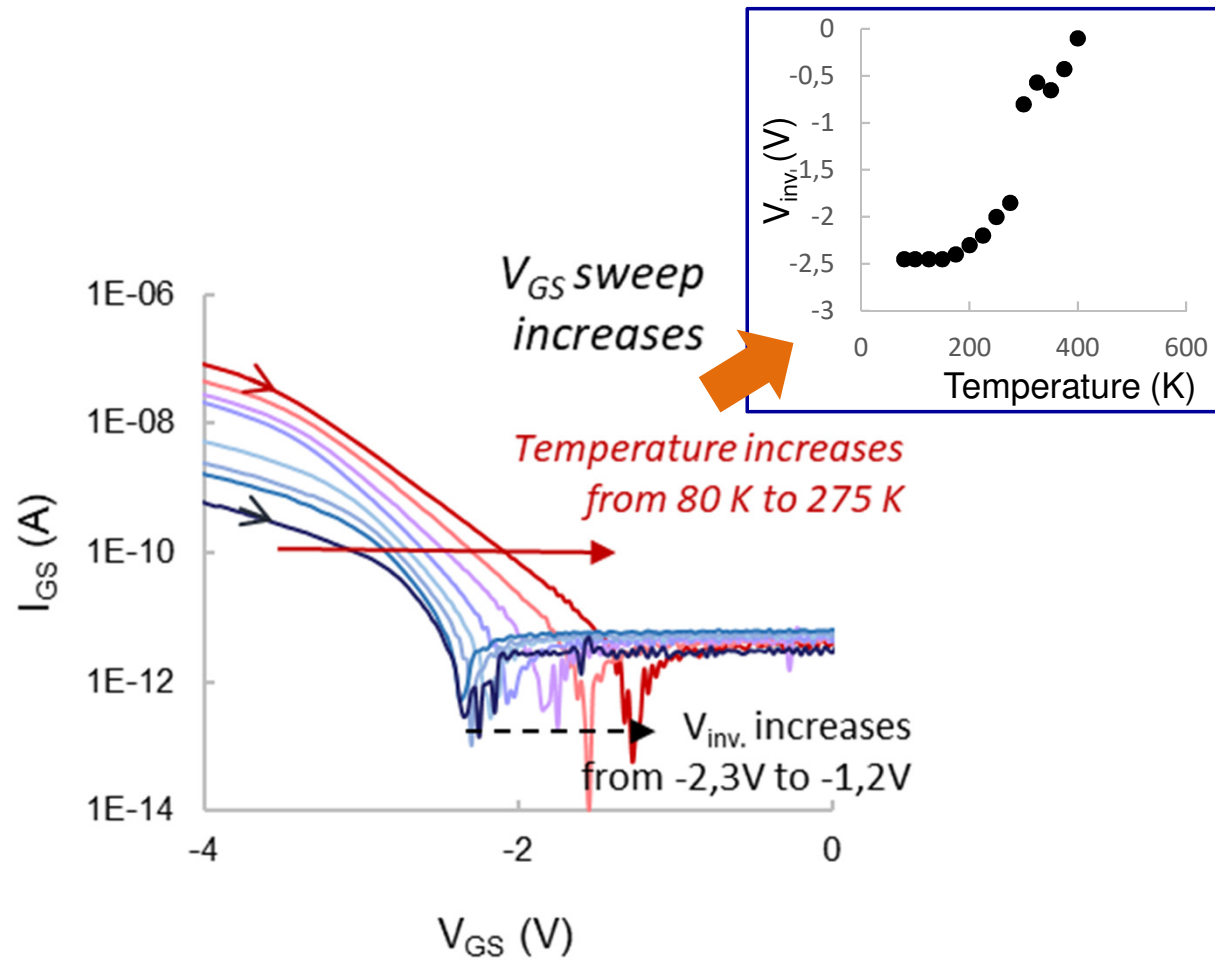
② donor-traps are ionized at very negative V_{GS}

Increasing V_{GS} from -6V to +3V:

Donor are ionized (N_{D^+}) at very low V_{GS} . These positive charges act as an internal generator which field is opposite to the applied voltage V_{GS} , and $V_{th-incr.} > V_{th-decr.}$ (thus $n_{i-incr.} < n_{i-decr.}$), till $V_{th-incr.}$. When the 2DEG starts to conduct electrons, ionized donor-traps recombine with electrons from the 2DEG (few electrons that do not change n_i), and become passivated. The internal generator disappears and V_{th} changes to a lower value as for the decreasing sweep)

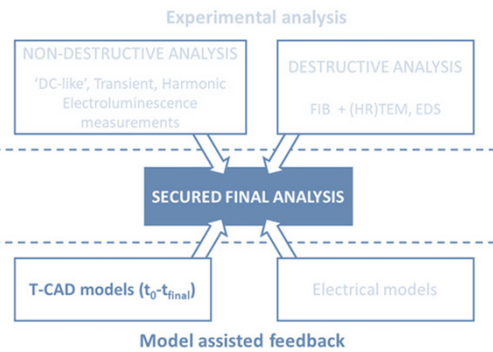
Thermal charac: $V_{inv.}$ drift (incr. decr. V_{GS} sweeps)

- Also noticed : $V_{inv.}$ drifts with temperature and depends on V_{GS} sweep direction

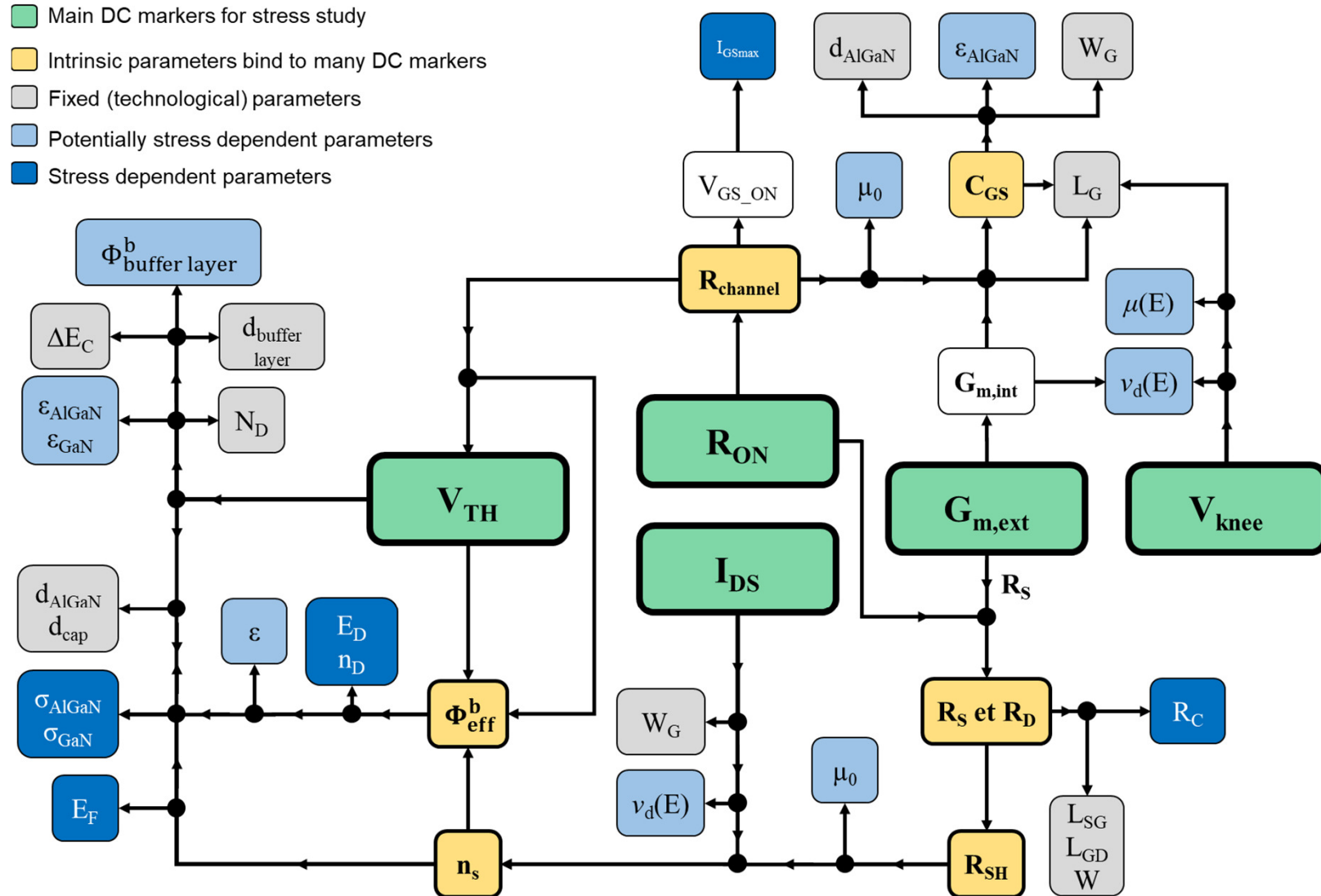


► CASE STUDY: AlGaN/GaN GH50 & GH25-10 (UMS)

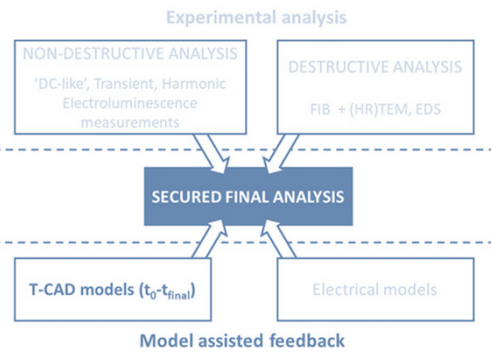
- Main DC markers for stress study
- Intrinsic parameters bind to many DC markers
- Fixed (technological) parameters
- Potentially stress dependent parameters
- Stress dependent parameters



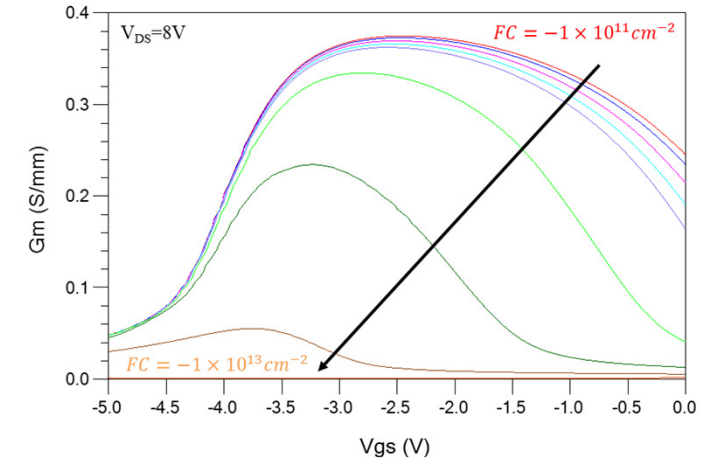
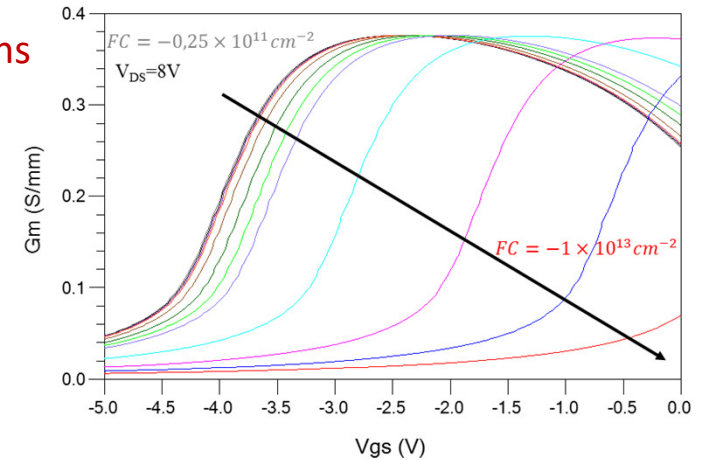
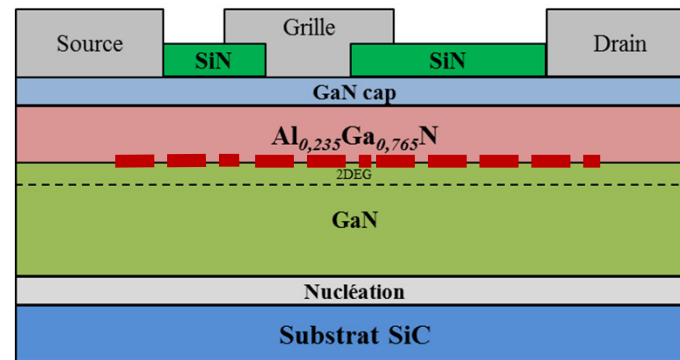
► Considering an accurate procedure for T-CAD model instruction



► CASE STUDY: AlGaN/GaN GH50 & GH25-10 (UMS)



SENTAURUS Software **Fixed Charges variations @ interfaces (ΔFC)**



► Considering an accurate procedure for T-CAD model instruction

ΔFC at AlGaN/GaN/2DEG are the more sensitive (vs AlGaN/GaN GaNcap or GaNcap SiN)

$\Delta FC = 3 \cdot 10^{12} \text{ cm}^{-2}$ explains both

- 1V V_{th} shift
- 30% I_{DS} reduction

Reliability studies; example of an academic methodology and tools for non destructive defect analysis

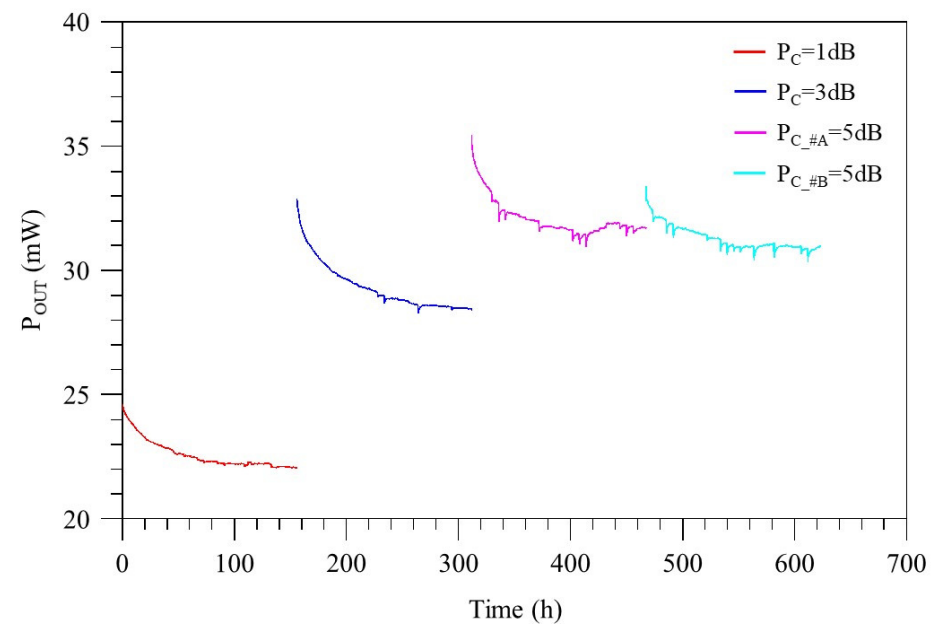
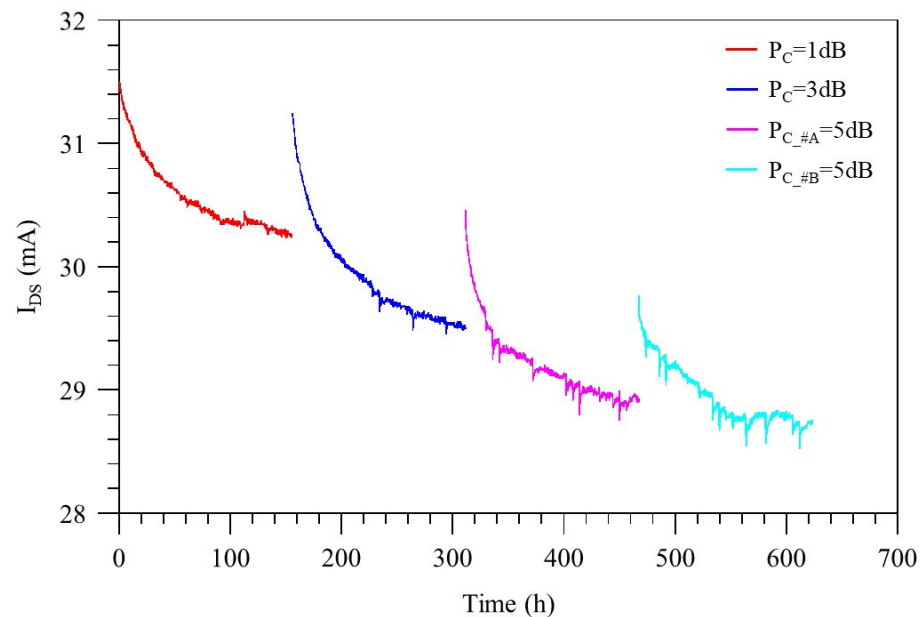
▶ RF-stresses of HEMT at x-dB compression (AlGaIn/GaN 2x0,15x50 μm^2)

-Under 1dB, 3dB, 5dB output compression, also tracking [S] parameters

Static-Dynamic correlations: ORIGIN(S) of the defects (direct proof? Speculative assumptions?)

Static+RF+[S]-param \rightarrow useful for technological development to remove speculative assumptions on degrad. Origin

- ▶ RF stresses @ $P_{x\text{dB}}$, each for a 156h period (624h cumulated)
- ▶ 3 D.U.T.s biased under $V_{\text{DS}}=15\text{V}$ & $I_{\text{DS}}=0,33\text{ A/mm}$, class A operation



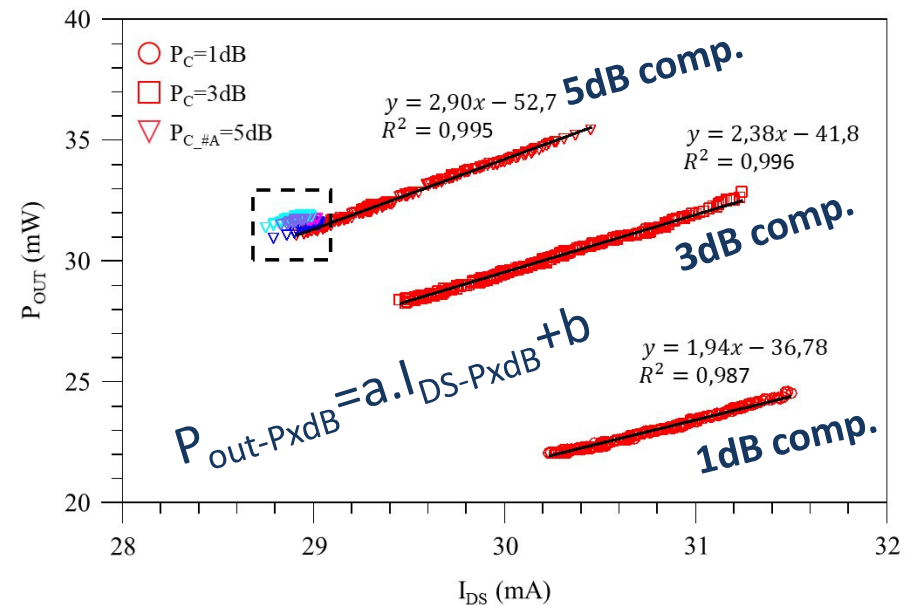
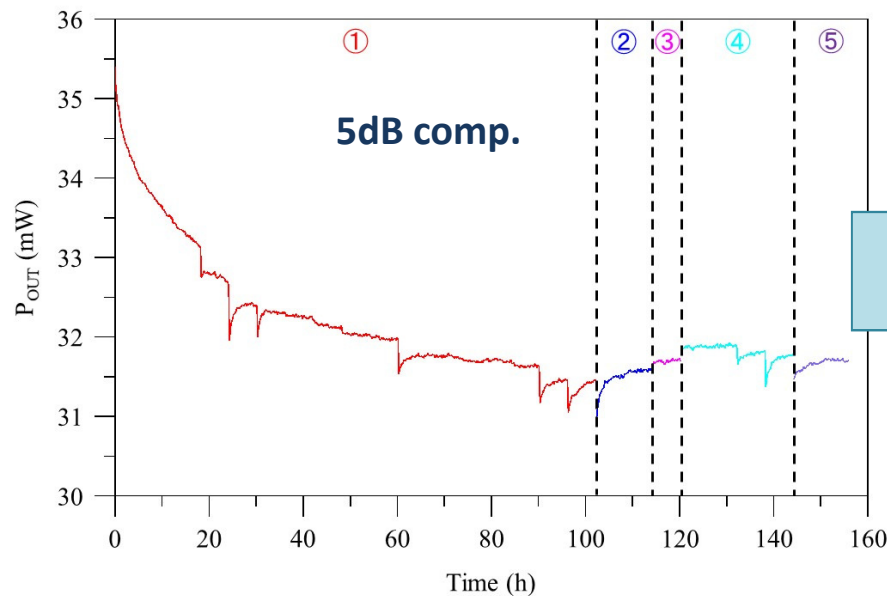
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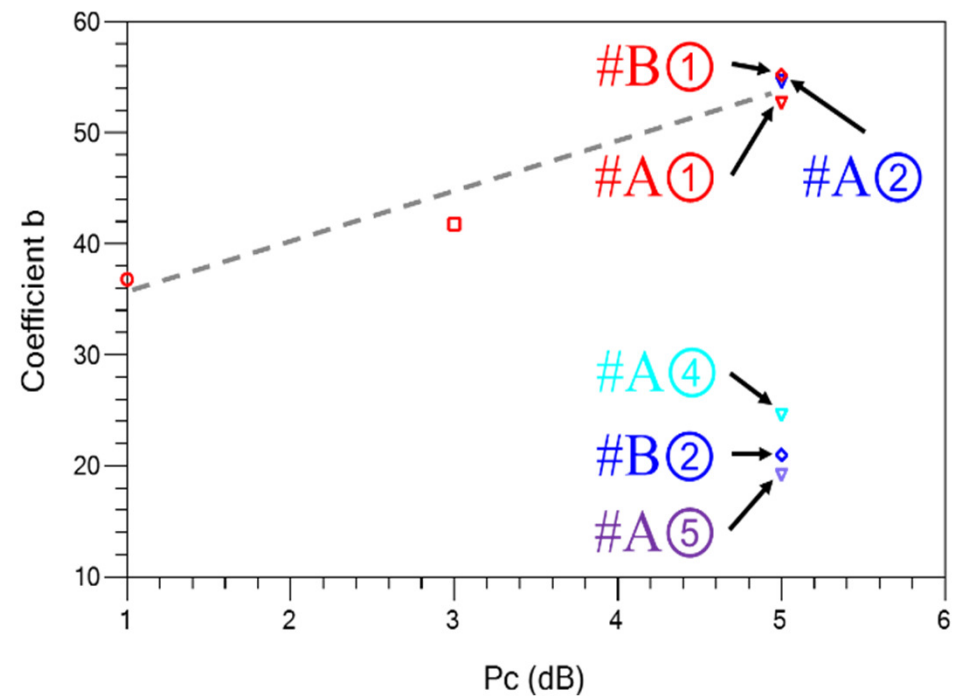
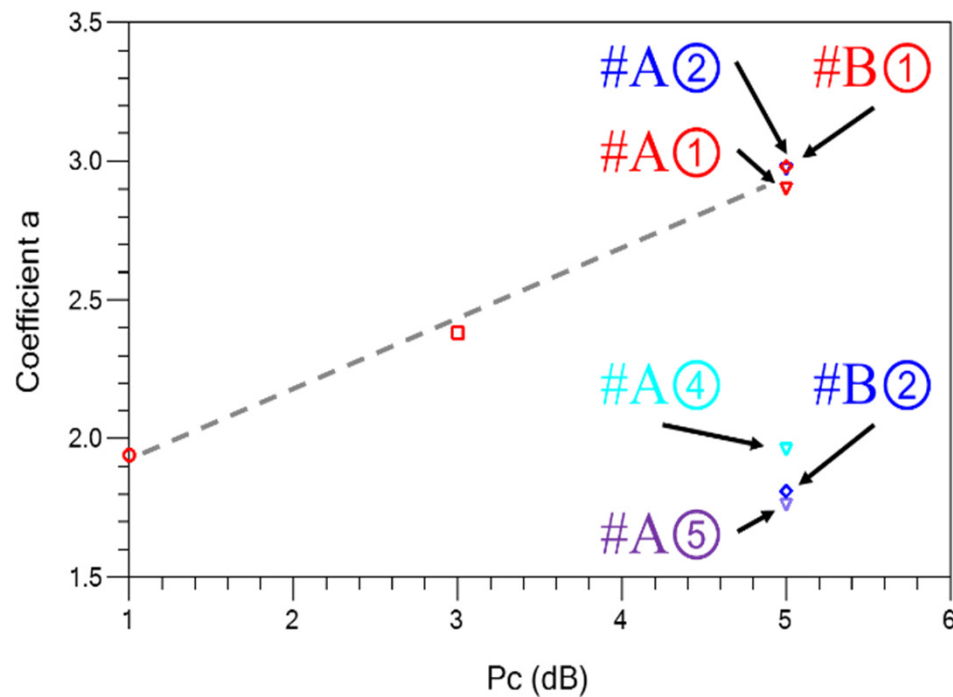
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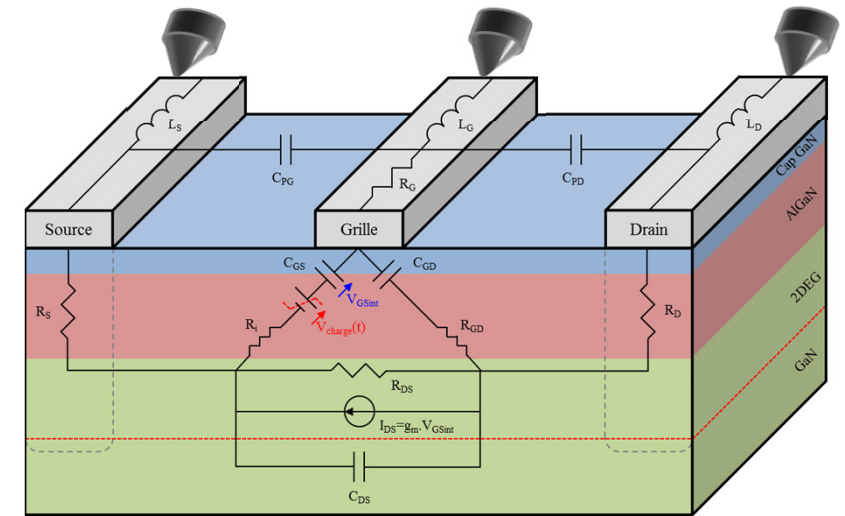
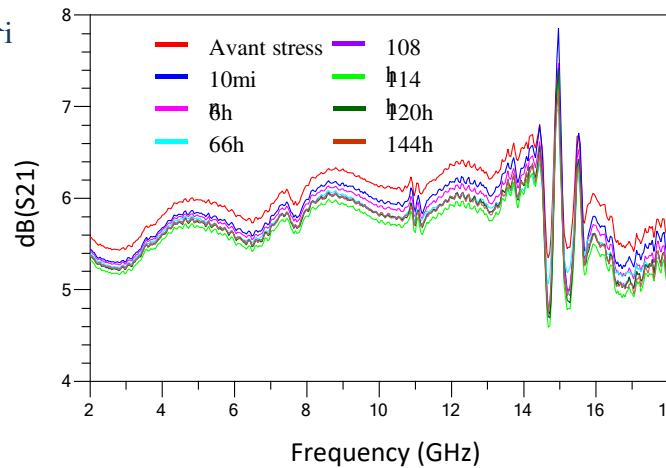
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Reliability studies; example of an academic methodology and tools for non destructive defect analysis

- ▶ RF-stresses of HEMT at x-dB compression (AlGaIn/GaN 2x0,15x50μm²)
- ▶ S21 variations correlated to P_{OUT} & I_{DS}

S₁₁, S₁₂ & S₂₂ parameters are stable
 → C_{GS}, C_{GD}, C_{DS}, R_{GD} & R_i
 not modified by stress
 (all dev. under test)

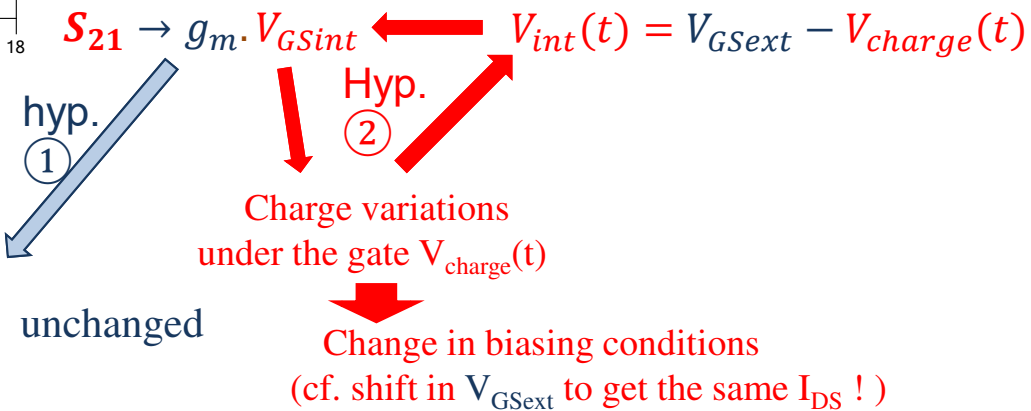


Where do variations on S₂₁ come from ?

S₁₁ does not change versus time during 1dB, 3dB, 5dB#A, 5dB#B
 S₂₁ changes (beginning, then stable) → change in V_{GS} to keep I_{DS}

→ Intrinsic charges under the gate modify the intrinsic V_{GS-int} controlling the 2DEG

C_{GS}
C_{GD}
R_i } unchanged

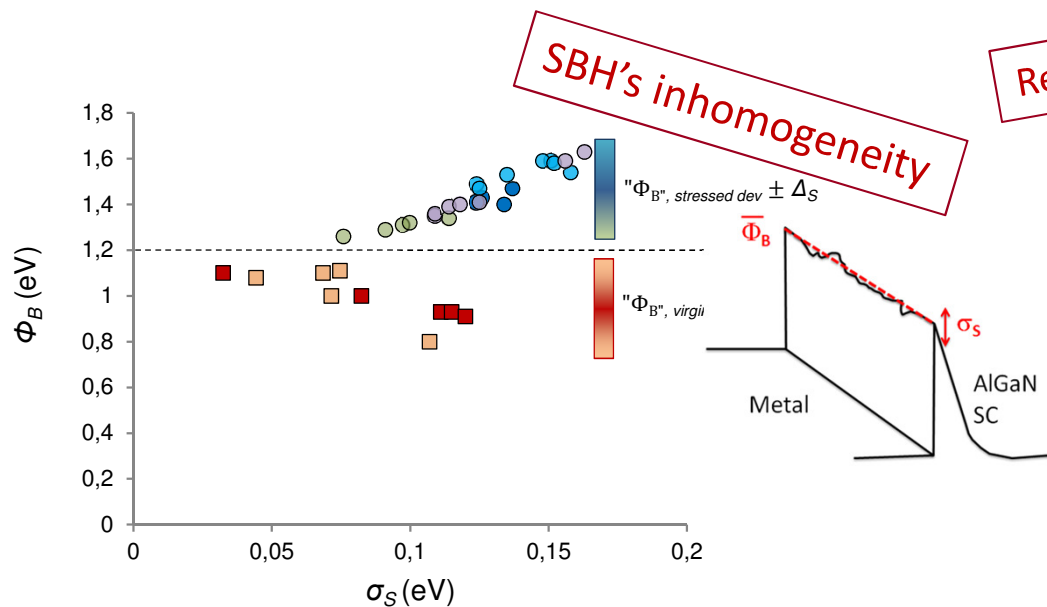


Reliability studies; example of an academic methodology and tools for non destructive defect analysis

► Assessment for location and nature of defects (but destruction of device)

Destructive tests performed by DGA (French DoD) and SERMA

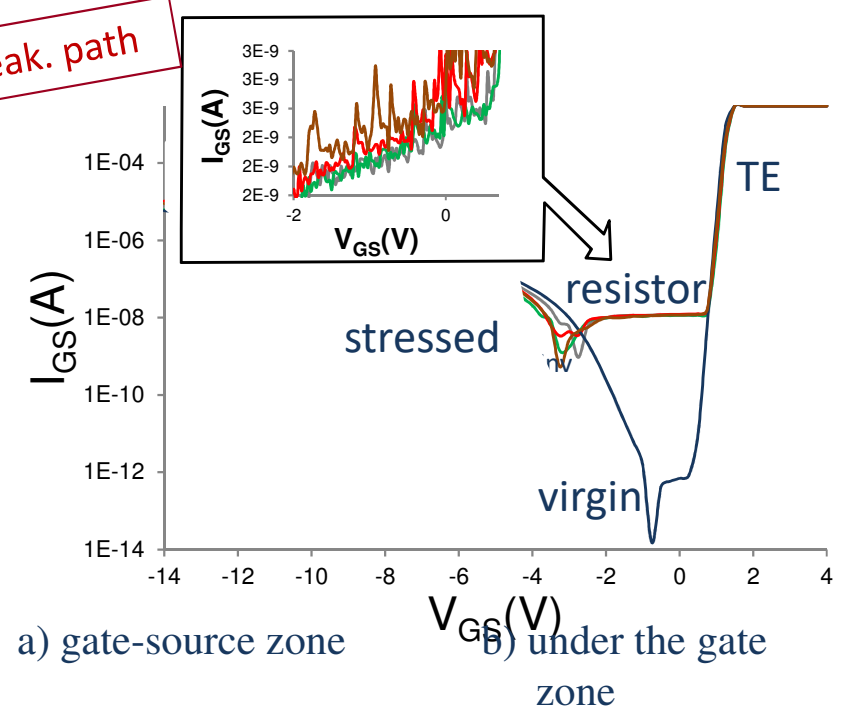
Top view of the gate finger



TEM lamella (after removing the gate pad)

Ref : Lazar, IEEE IMS 2013

STEM-HAADF images (FIB cut)



a) gate-source zone

b) under the gate zone

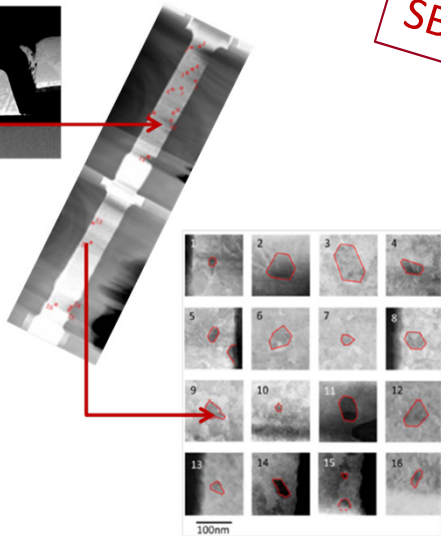
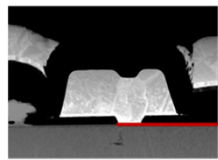
Ref : Tartarin, ESREF 2017

Reliability studies; example of an academic methodology and tools for non destructive defect analysis

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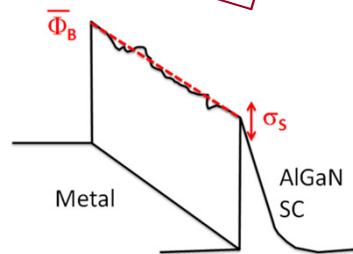
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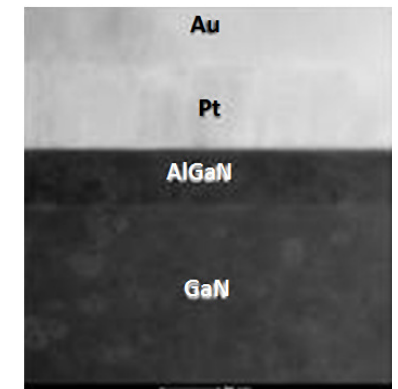
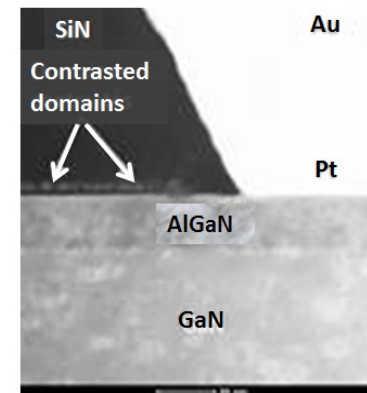


SBH's inhomogeneity

Resistive leak. path



STEM-HAADF images (FIB cut)



a) gate-source zone

b) under the gate zone

TEM lamella (after removing the gate pad)

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LES OUTILS DU LAAS, L'EXPERIENCE et LE POSITIONNEMENT NATIONAL/INTERNATIONAL

LES PROJETS DEPUIS 2002 + SUIVI DES ÉVOLUTIONS TECHNOLOGIQUES GaN
(substrats SiC, Si, GaN, Diamant)

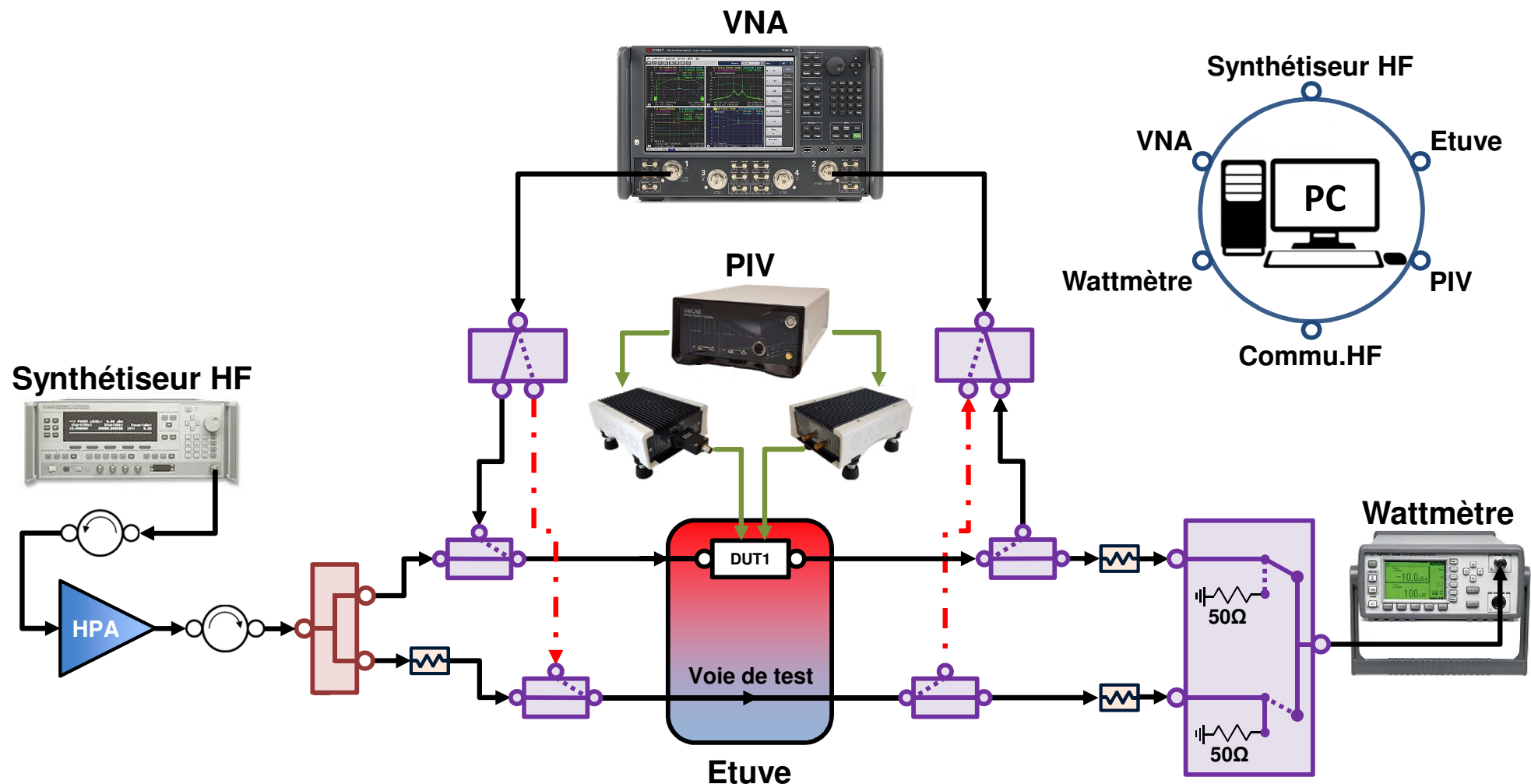
QUELQUES CAS D'ÉTUDES

LES PROSPECTIVES ET LES OPPORTUNITÉS VIA PROOF

SYNTHÈSE et DISCUSSIONS

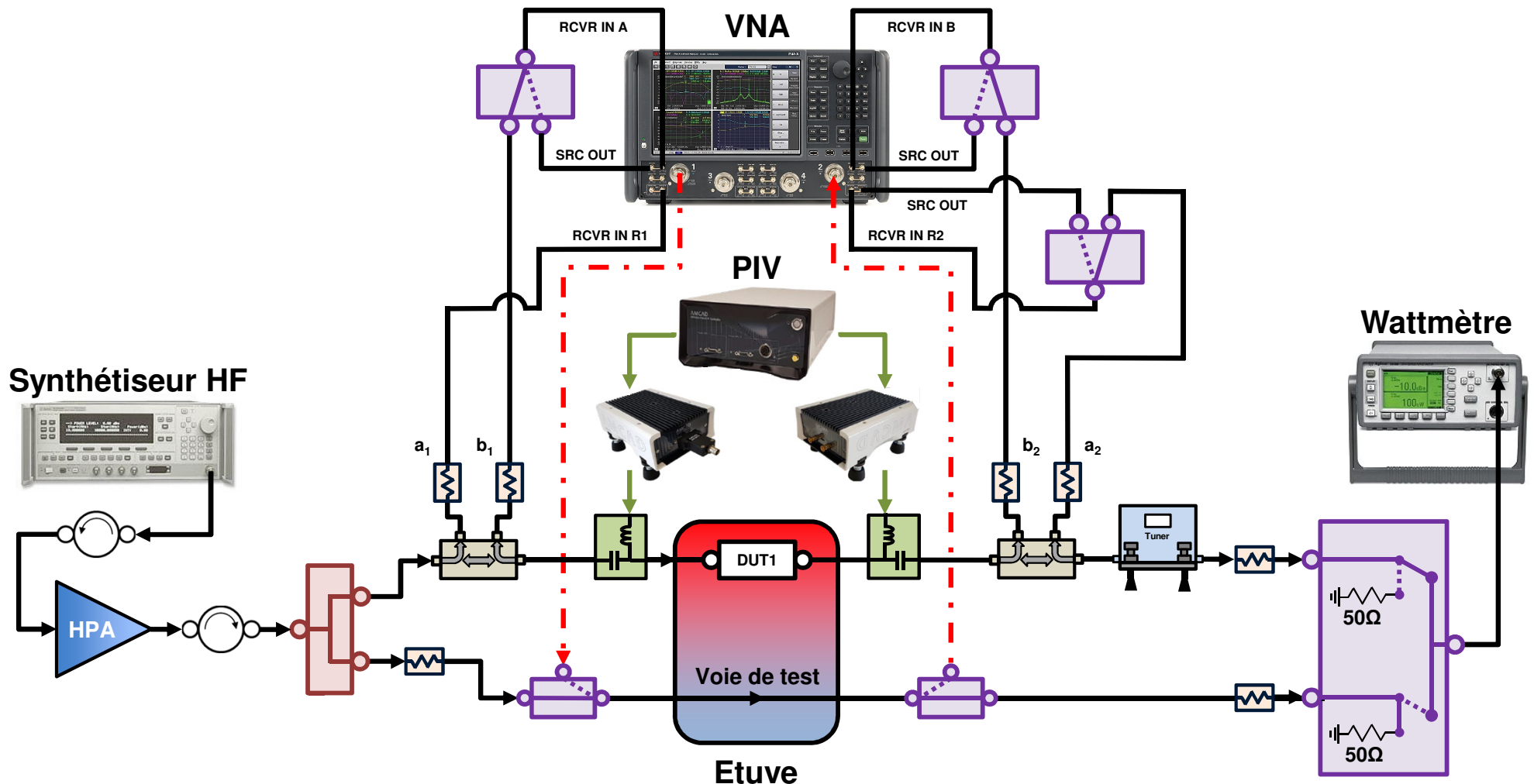
Evolution du banc de vieillissement

Synoptique général banc de vieillissement thermique à haute fréquence
*Configuration stress **circuit** en mode **pulsé***



Evolution du banc de vieillissement

Synoptique général banc de vieillissement thermique à haute fréquence
*Configuration **Load Pull** stress transistor en mode **pulsé***



-BRUIT HF (IEMN – couverture très hautes fréquences jusqu'à 300 GHz):

(LAAS 1-40 GHz, pas de spécificité LAAS sur les 4 param. de bruit)

PROOF → banc de stress avec NF50 intégré au VNA (LAAS)

-BRUIT BF (XLIM et IMS - aquitaine):

LAAS référencé centre Européen (4 bancs, LFN + RTN – S_{ID} & S_{IG}).

LAAS : Nombreuses études de cas multi-physiques (DC, transitoire, pulsé, param. S, TCAD)

PROOF → analyses de reprises durant stress (analyse fine des évolutions des défauts)

-Analyse pulsée P2P (IEMN et XLIM): bancs sous pointes solution AMCAD

PROOF : PIV-param-S pulsés INTÉGRÉ au banc de stress RF – thermique (unique)

Ajout mesures émulation « multi-porteuses par bruit blanc » (court/moyen terme)

Selon besoins, analyses multi-signaux EVM-APCR-NPR (diag. Œil) –selon intérêt partenaires et financement –

toujours en approche STRESS RF

-Analyse de fiabilité (IMS et LPN)

PROOF : STRESS RF +thermique avec mesures intégrées $S_{pulsées}$, NF50, PIV

mesures de reprises LFN et

PULSÉ : - sous pointe @ Temp.stress constante (1 voie)

- en boîtier avec cyclage thermique (1 voie, sinon duplication des PIV pour chaque voie)

CW (déjà en place [S-CW]) : possibilité d'aménagement [S-pulsé] et NF50 en mesures intermédiaires

(effets de charges en quasi isotherme) sur 4 voies.

